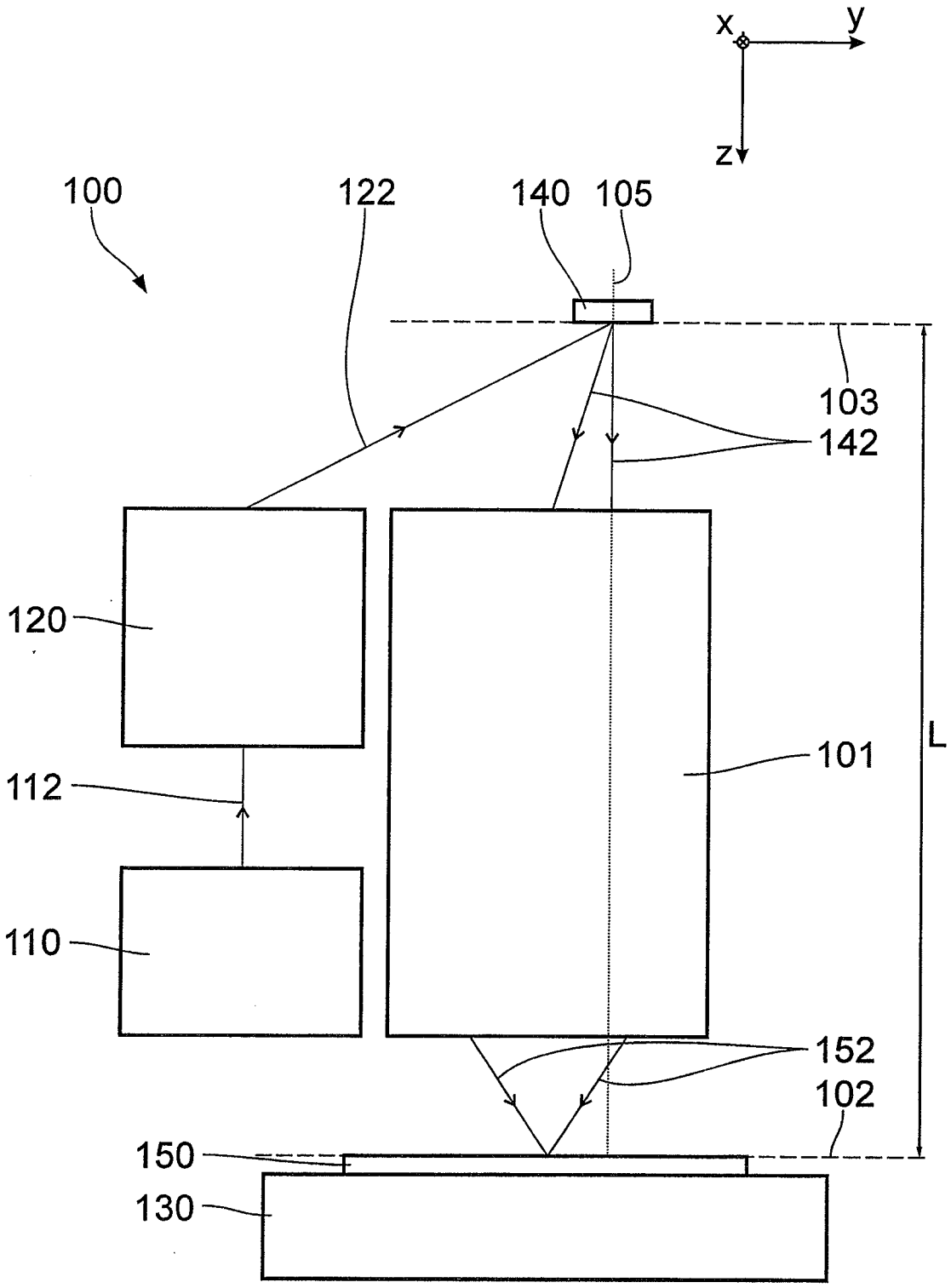


Fig. 1

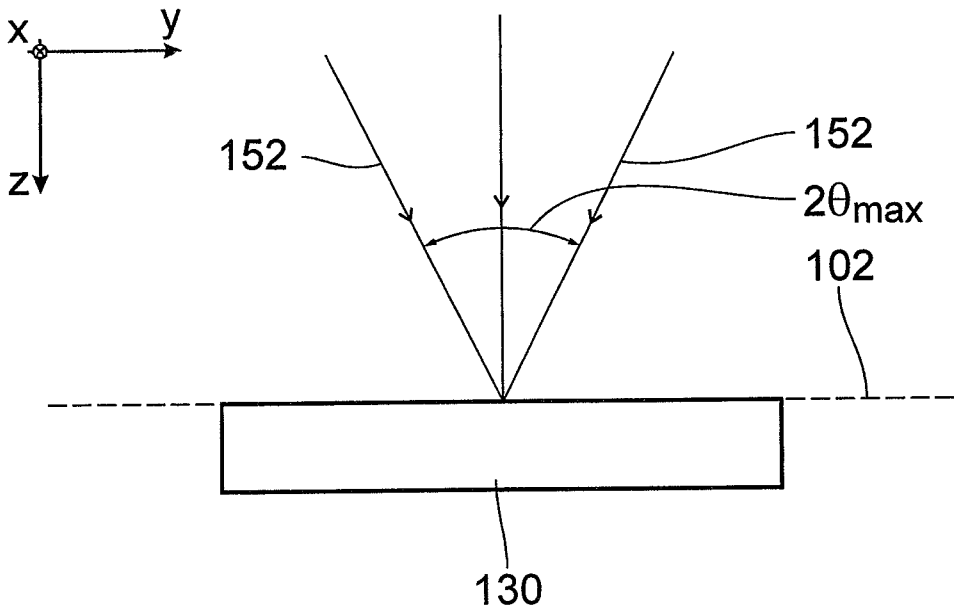

x
y
z
152
152
2θmax
102
130

Fig. 2A

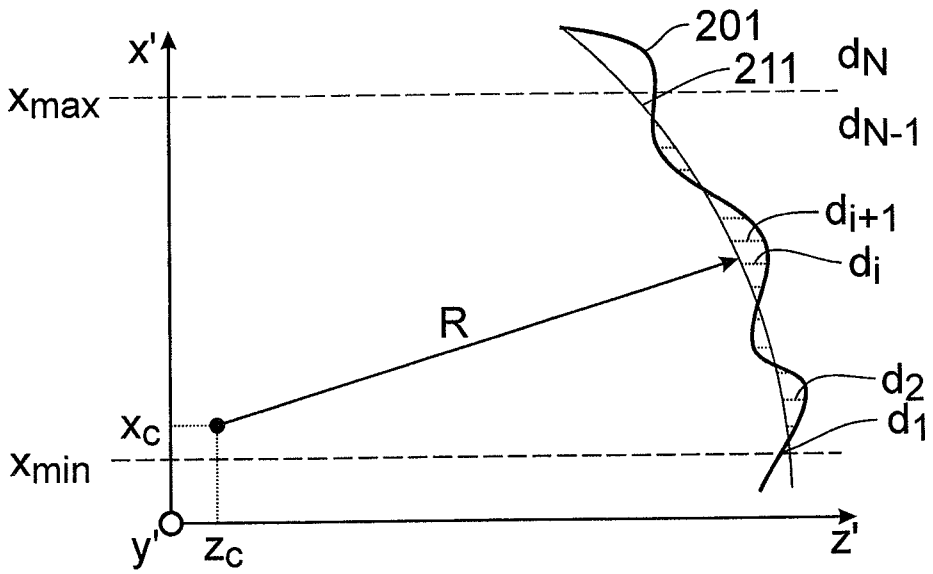

x'
xmax
xc
xmin
y'
zc
z'
R
201
211
dN
dN-1
di+1
di
d2
d1

Fig. 2B

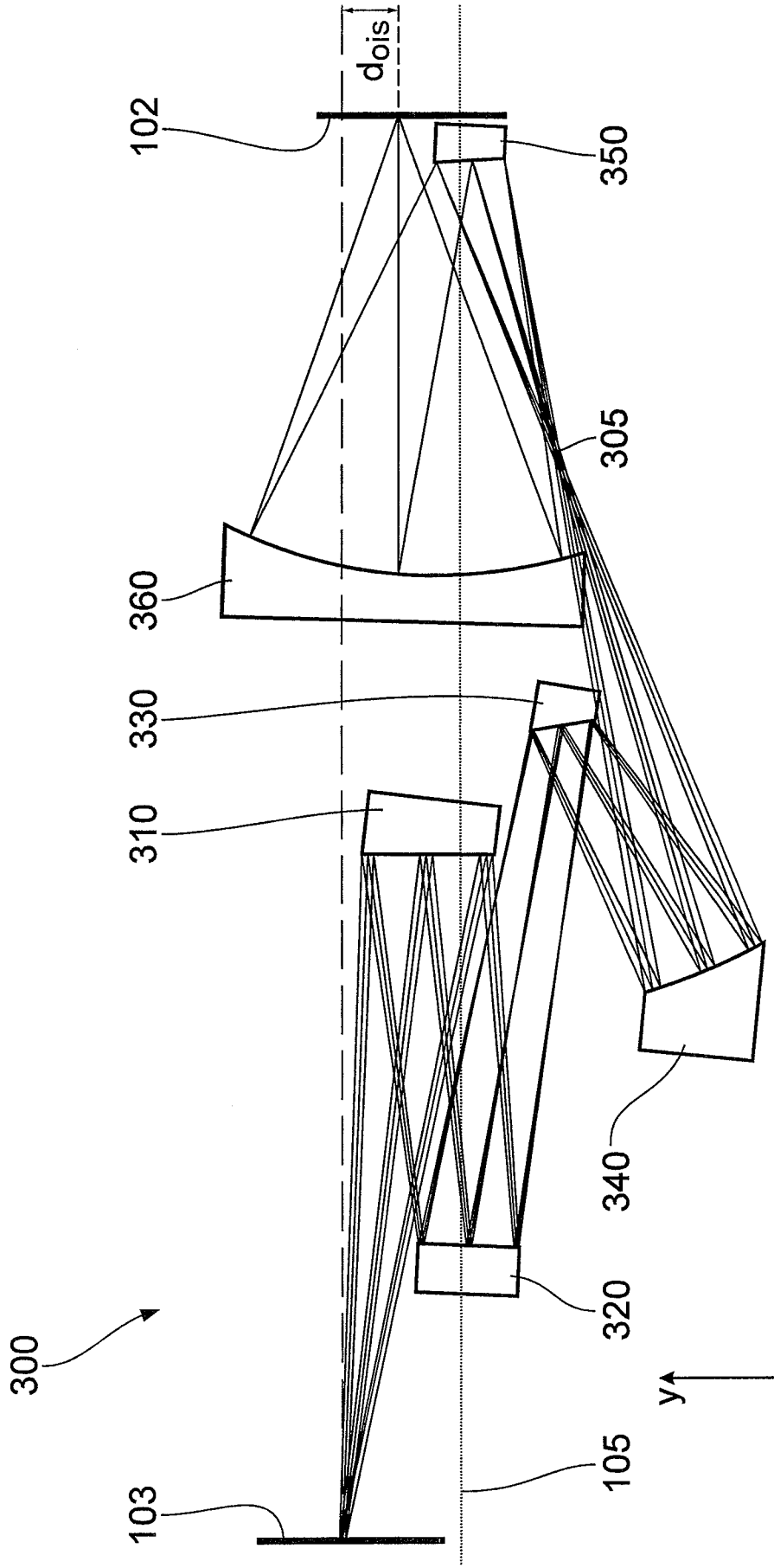


Fig. 3

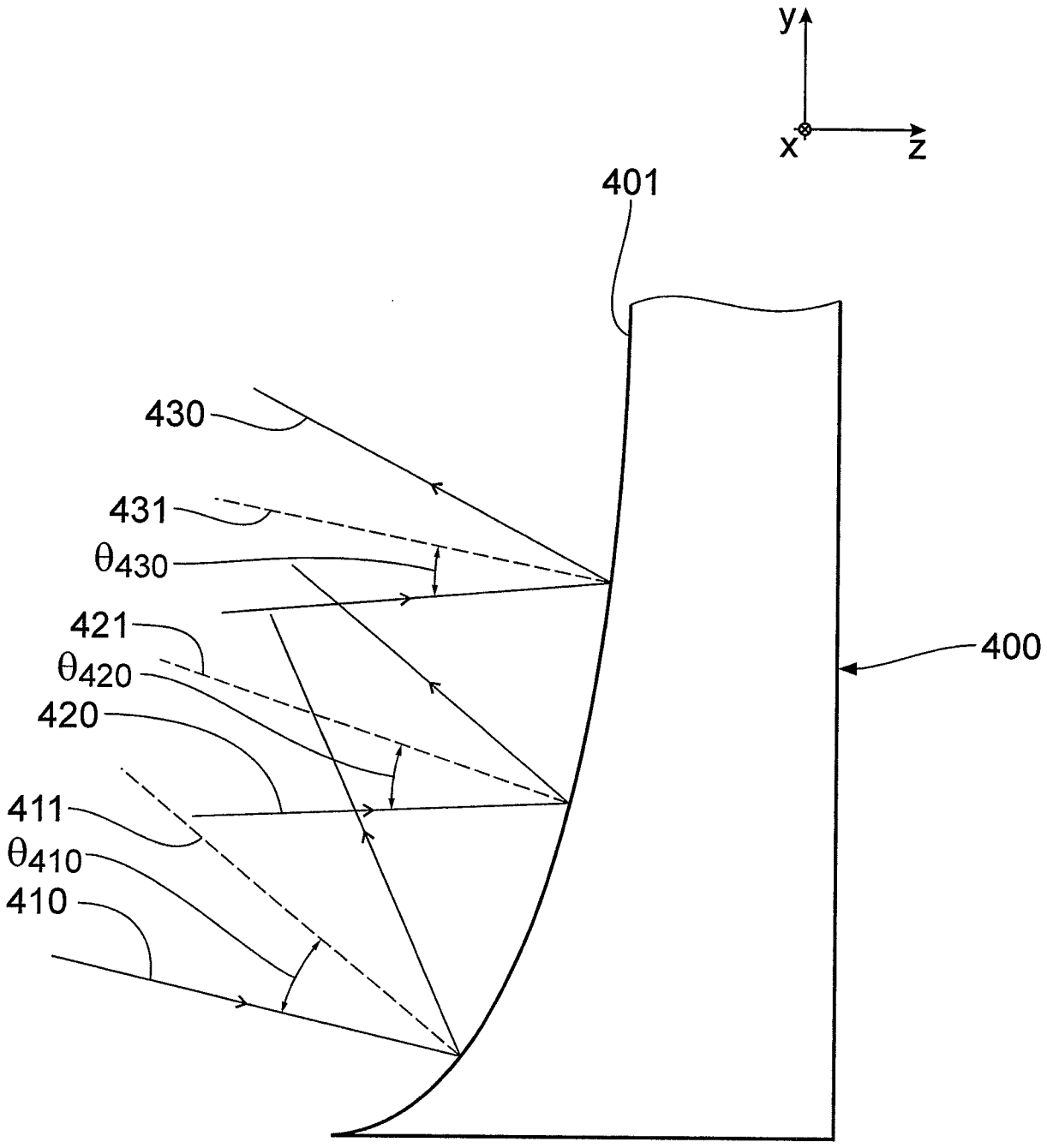


Fig. 4

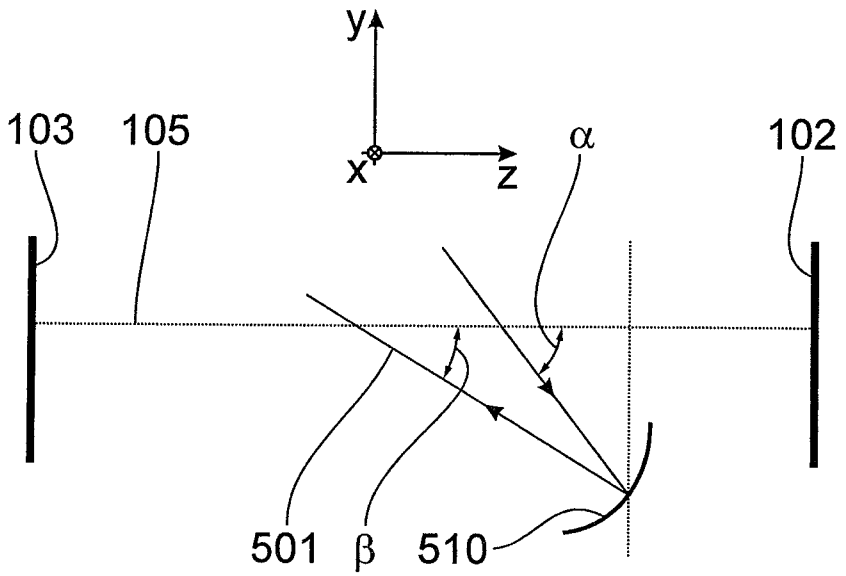


Fig. 5A

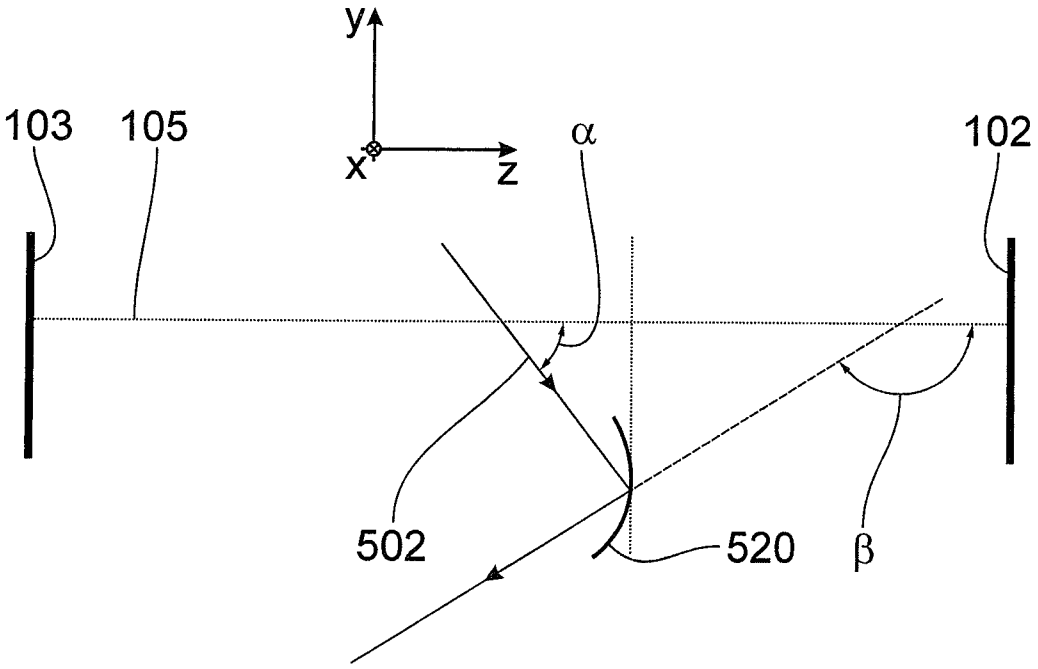


Fig. 5B

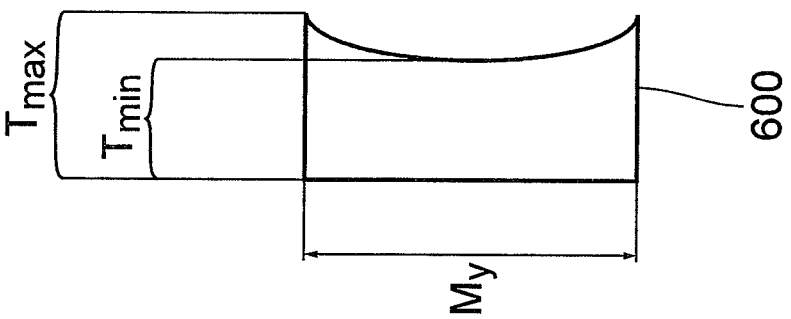


Fig. 6B

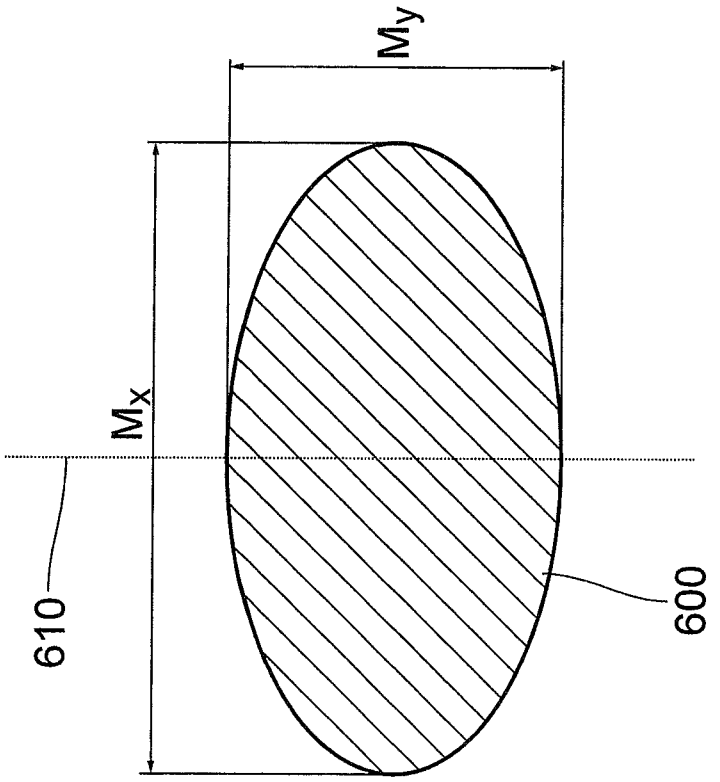


Fig. 6A

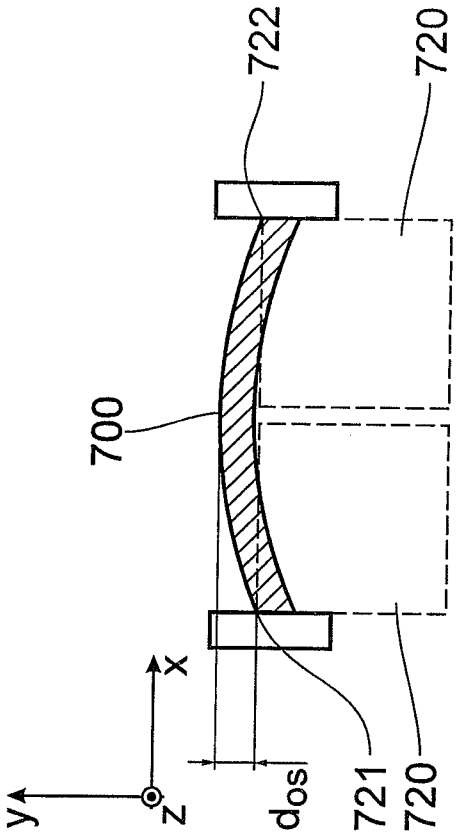


Fig. 7B

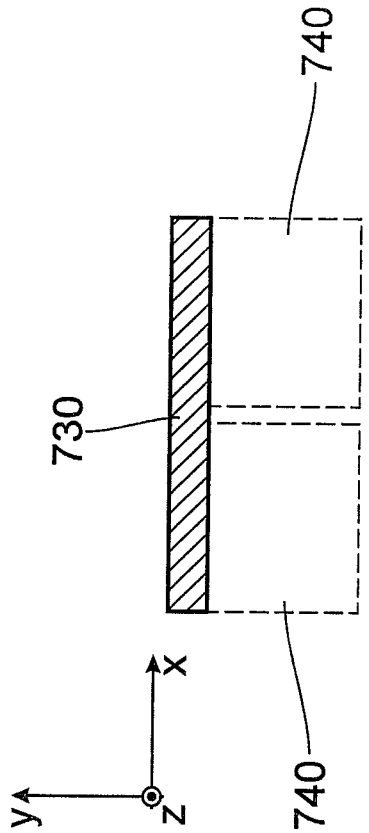


Fig. 7C

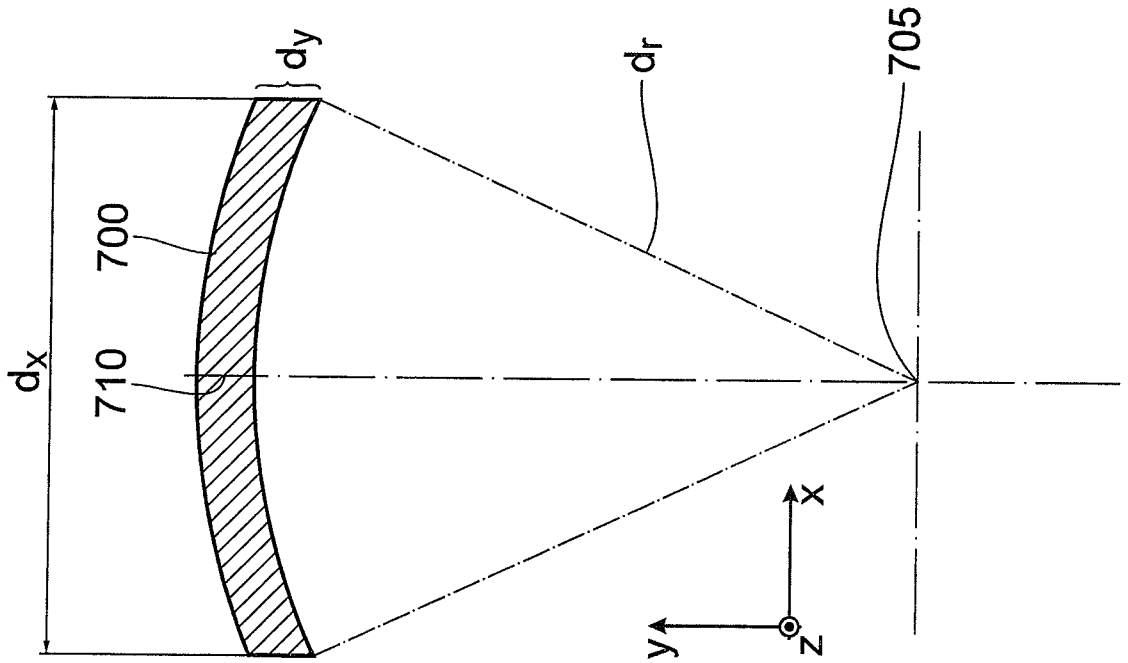
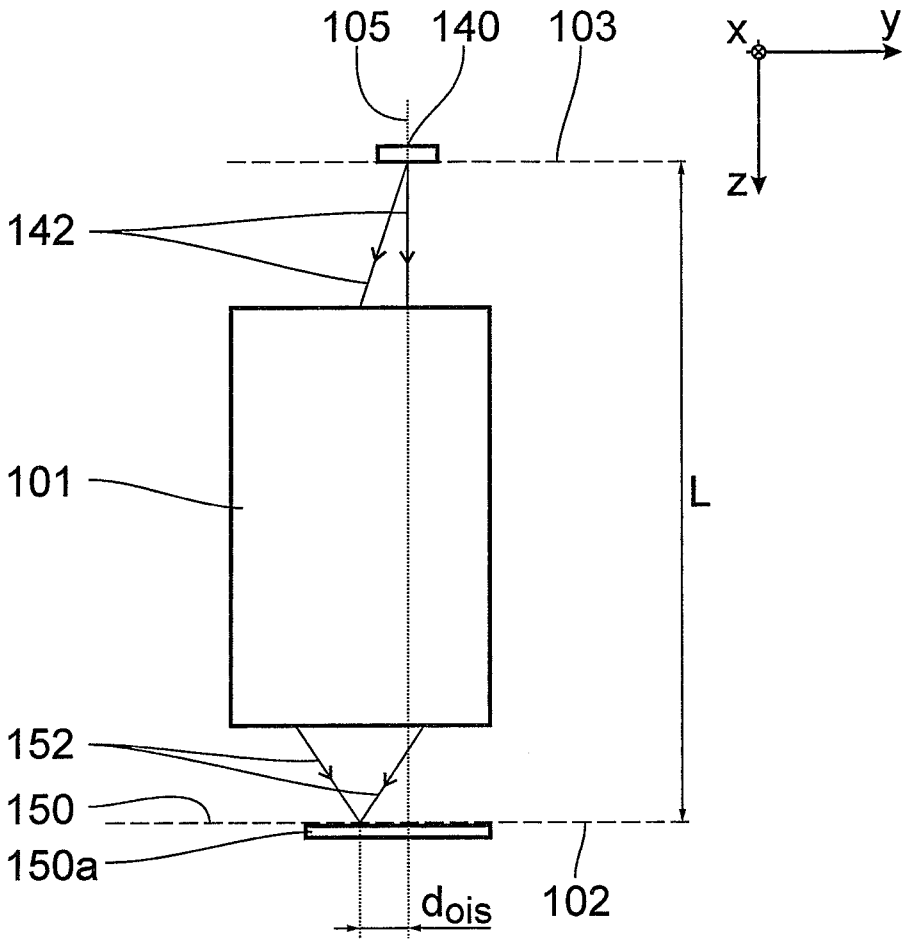


Fig. 7A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140
103
x
y
z
142
101
L
152
150
150a
102
d_{ois}

Fig. 8

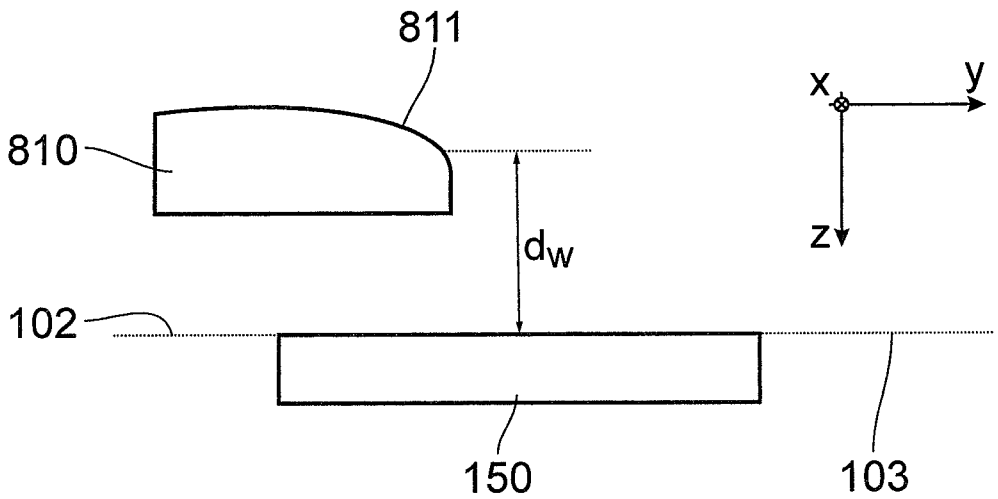

811
x
y
810
d_W
z
102
150
103

Fig. 9

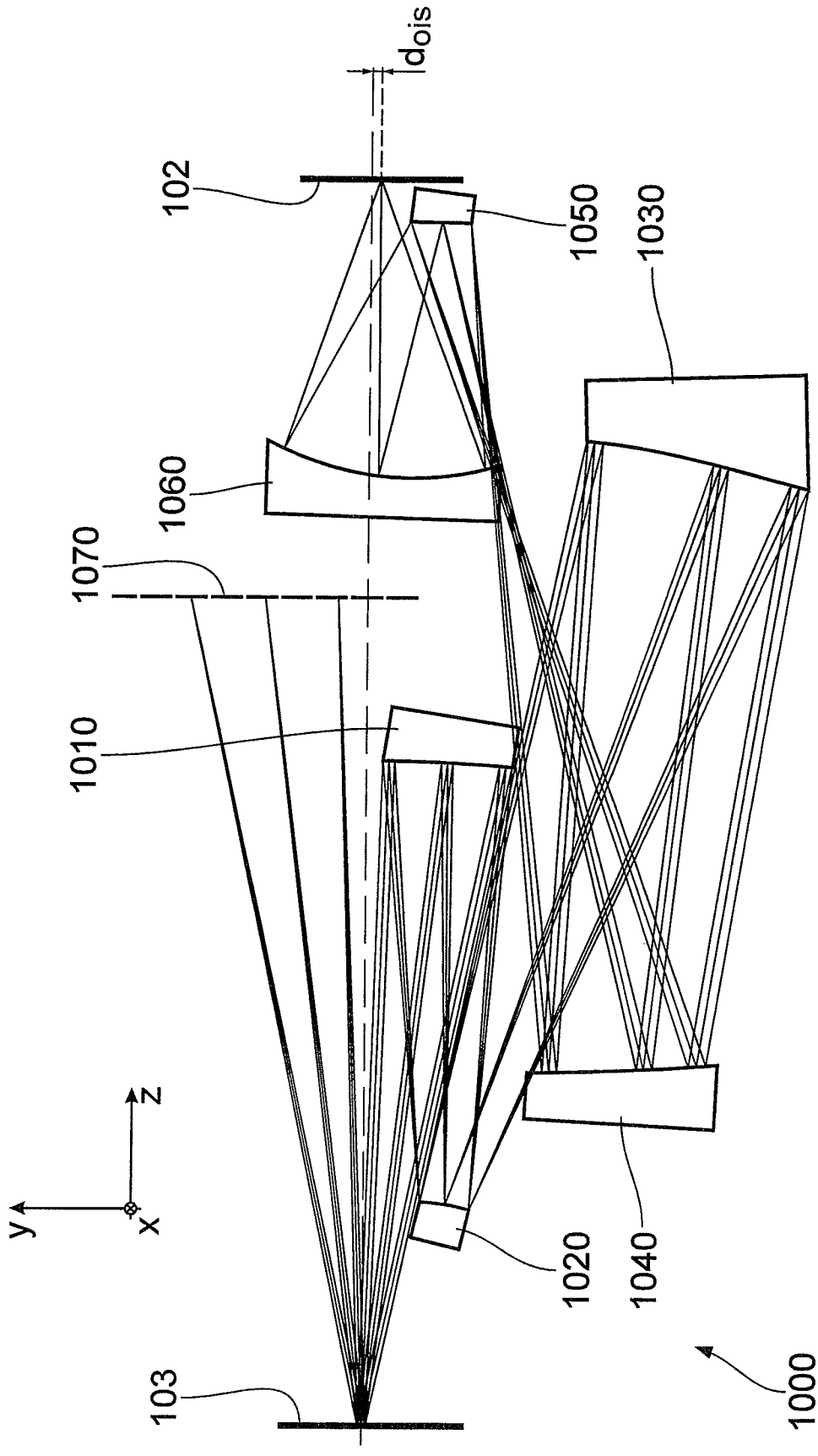


Fig. 10

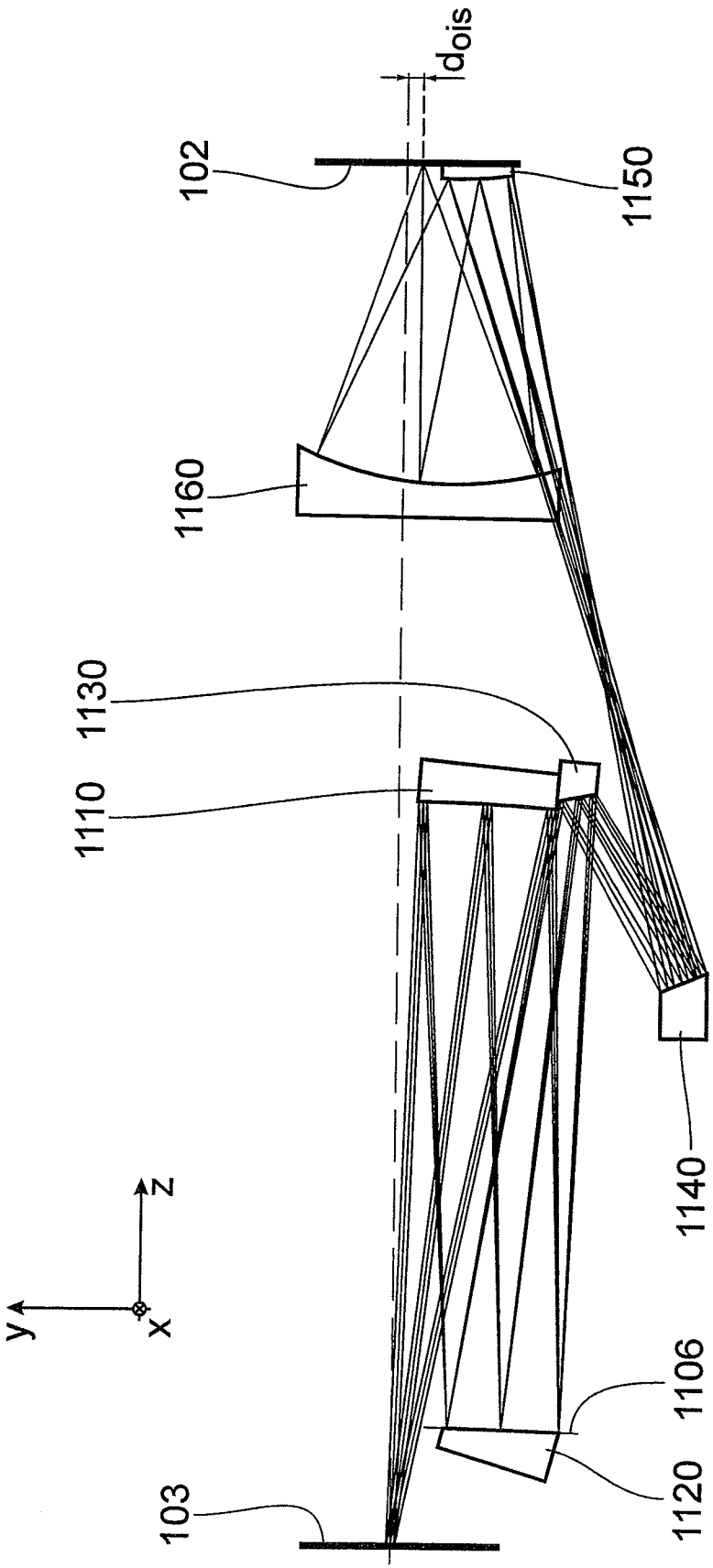


Fig. 11

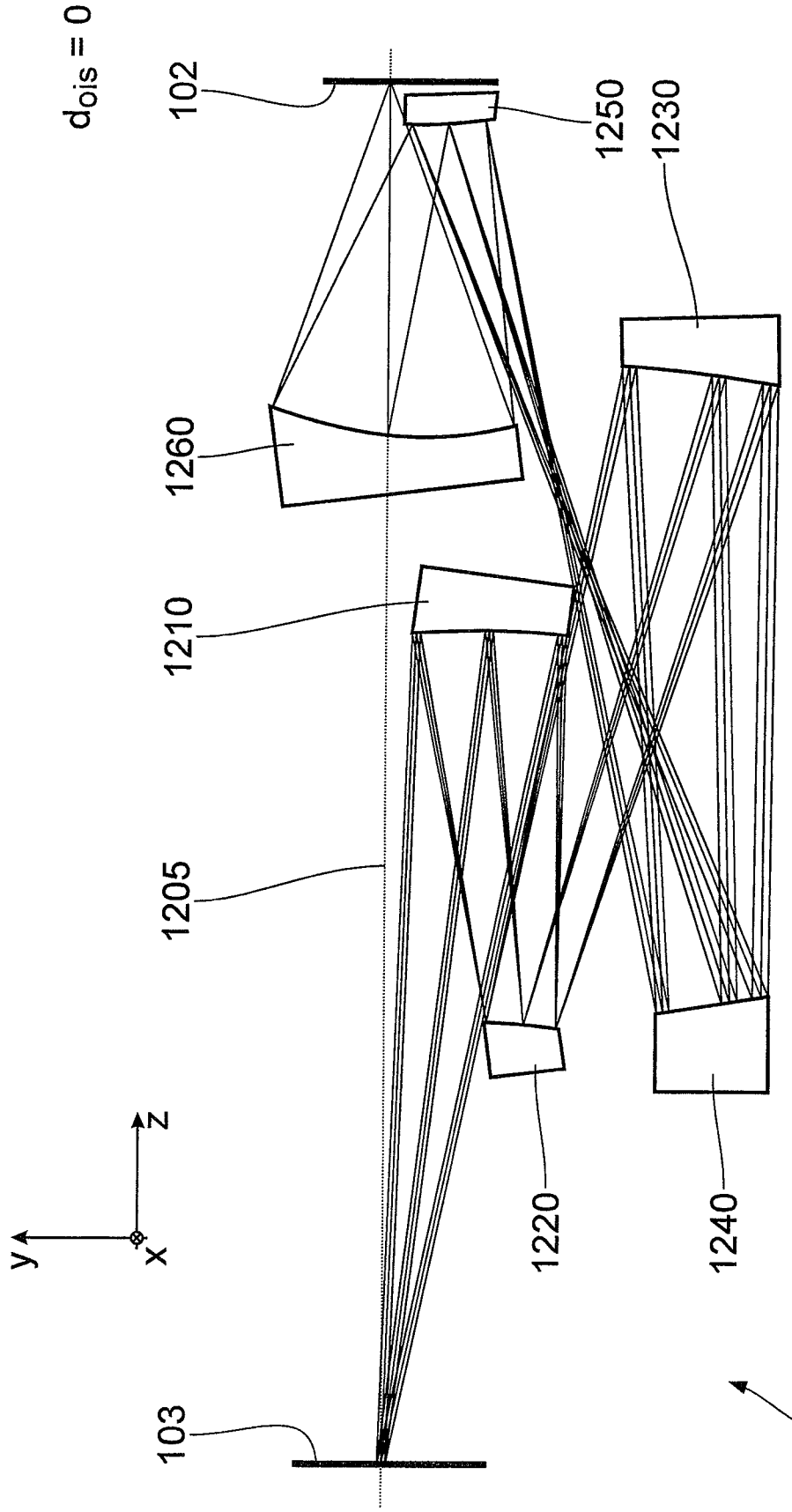


Fig. 12

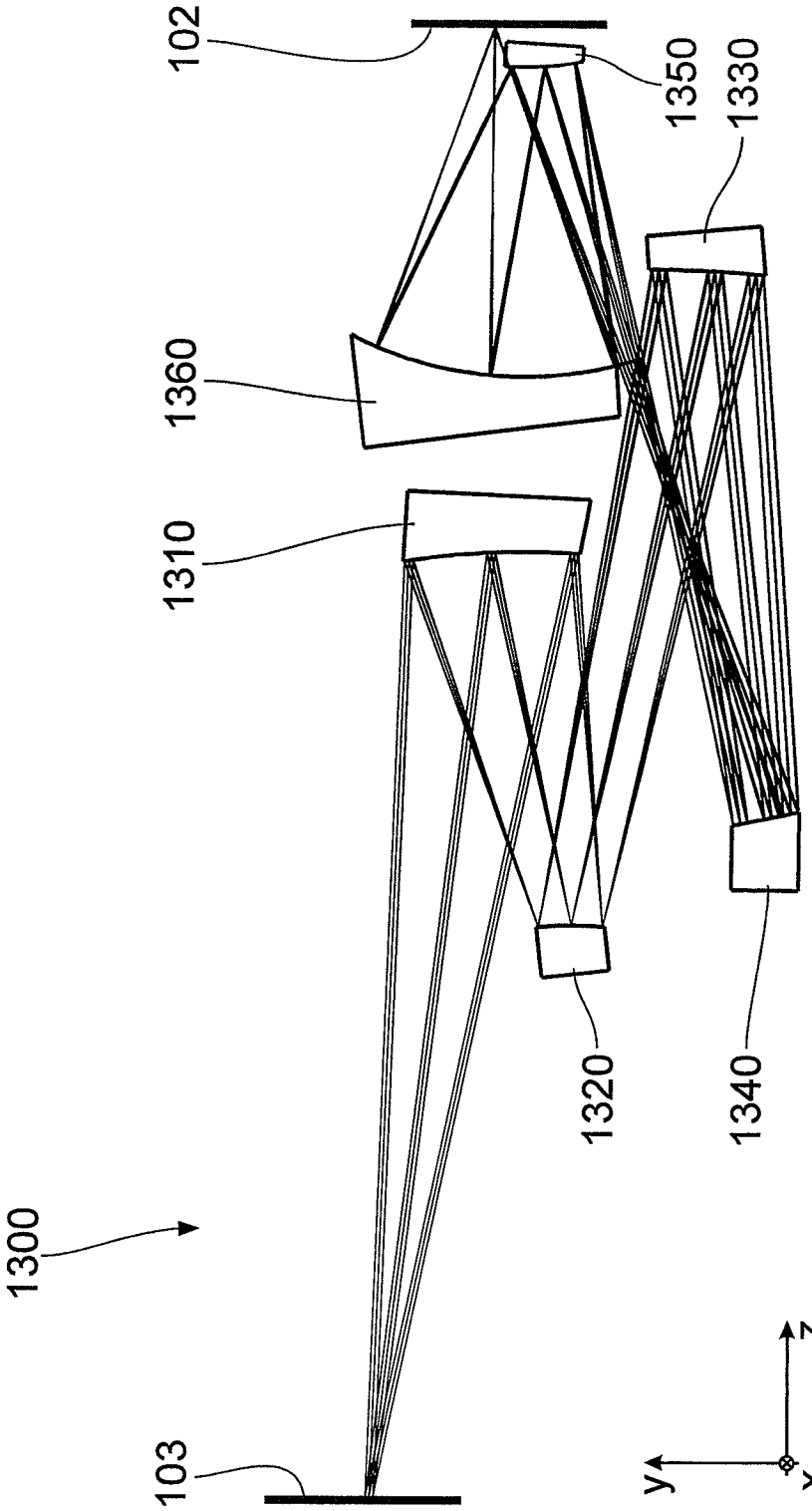


Fig. 13

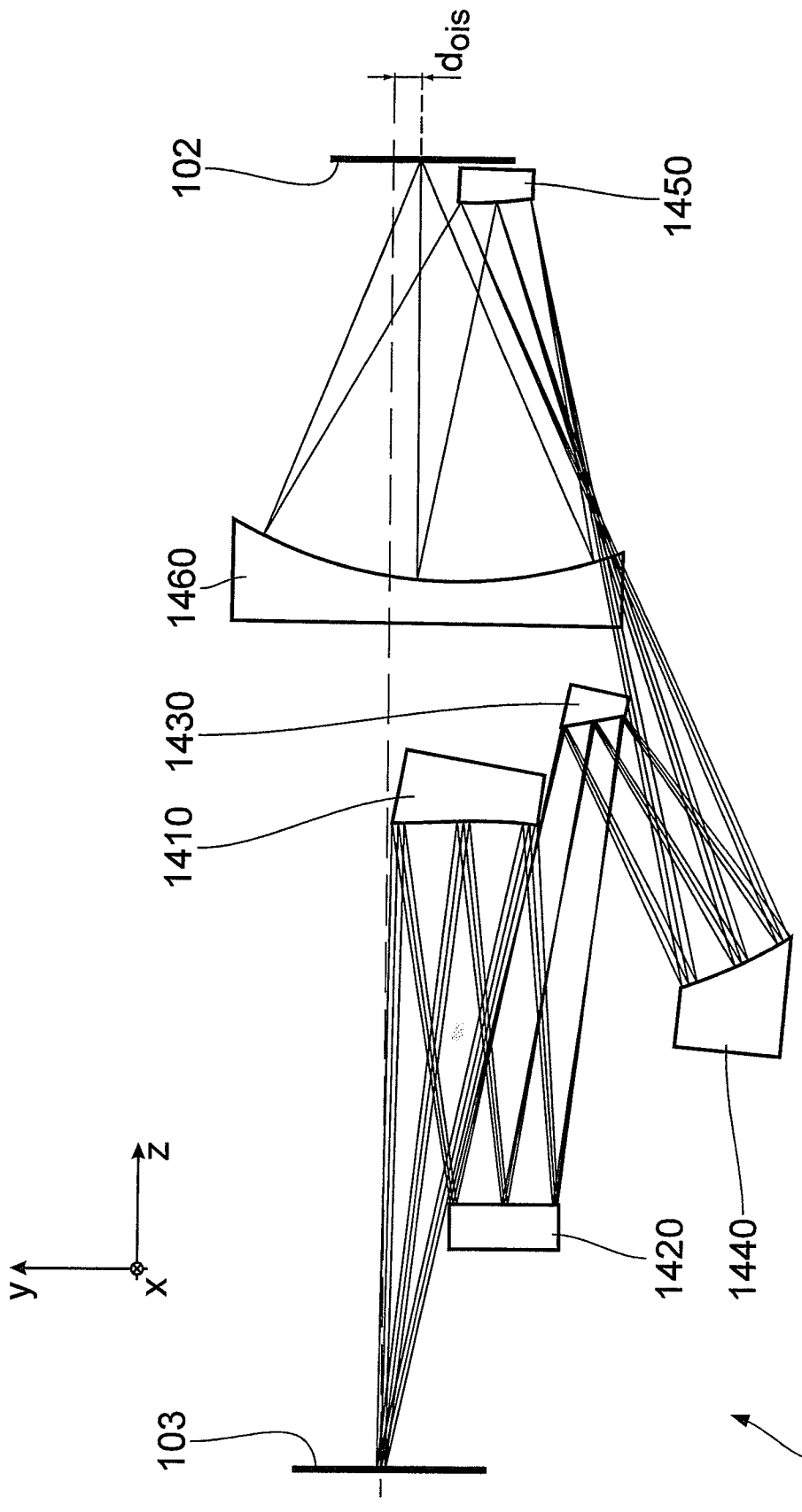


Fig. 14A

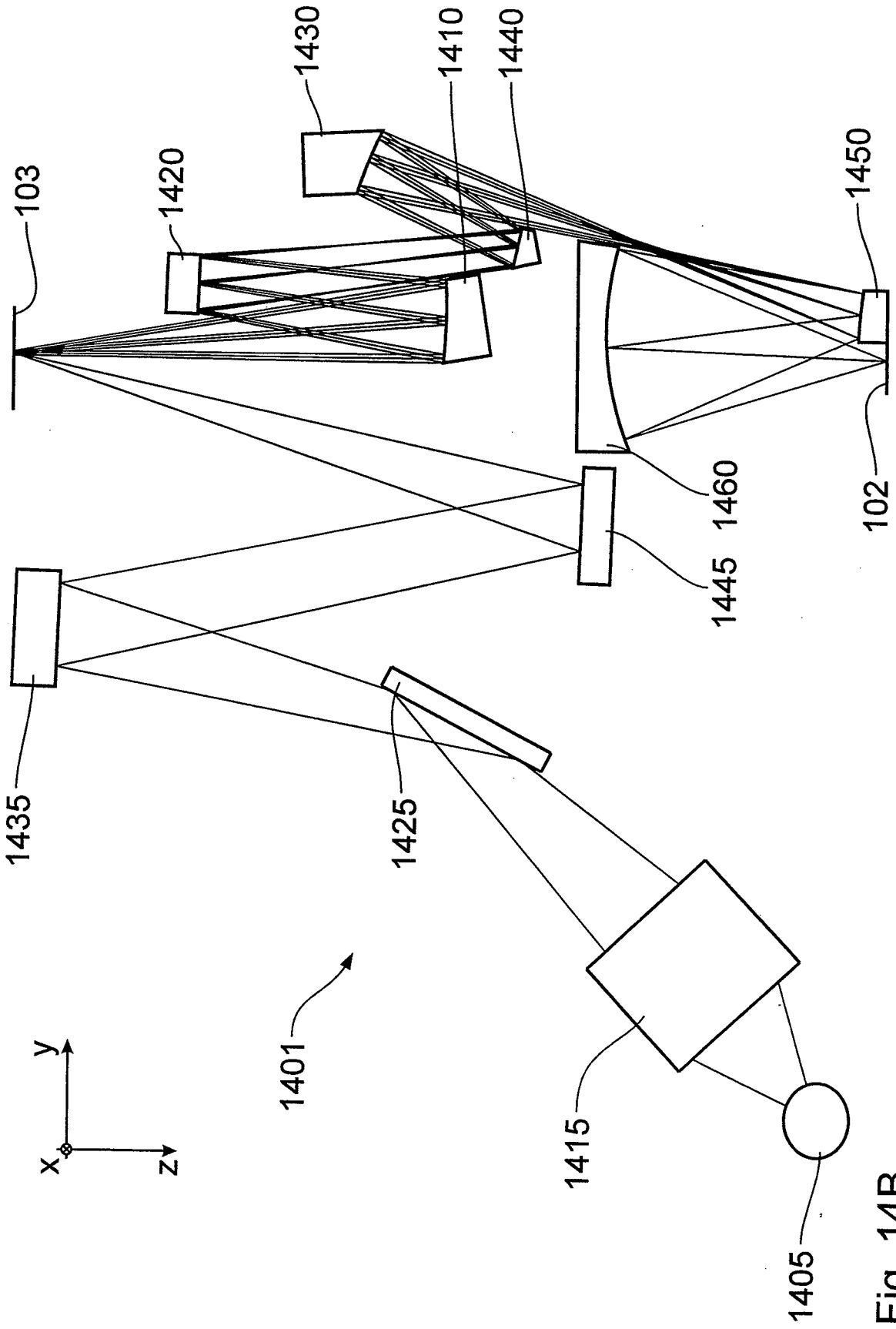

1430
1410
1440
103
1420
1450
1460
102
1445
1435
1425
1401
1415
1405
y
x
z

Fig. 14B

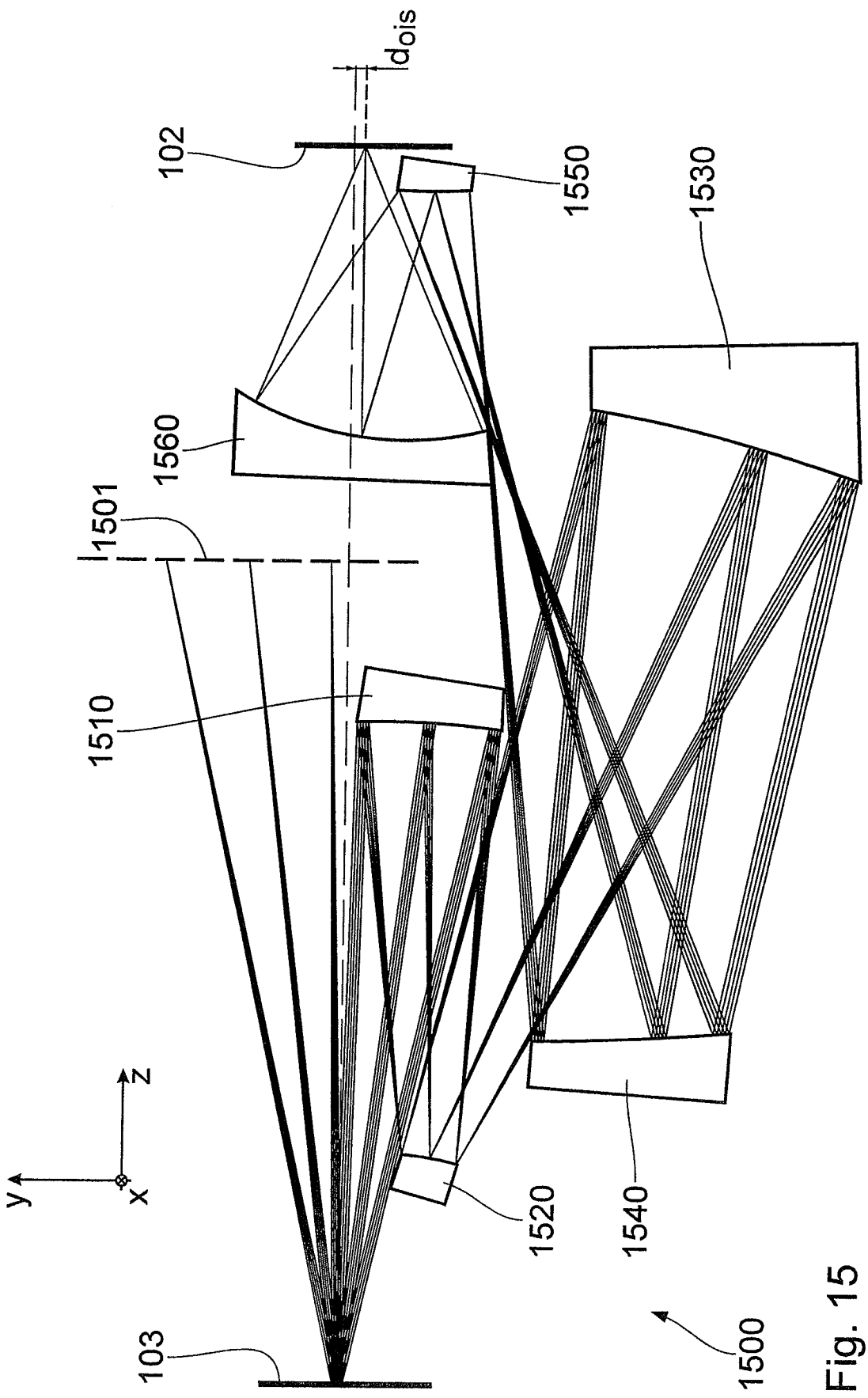


Fig. 15

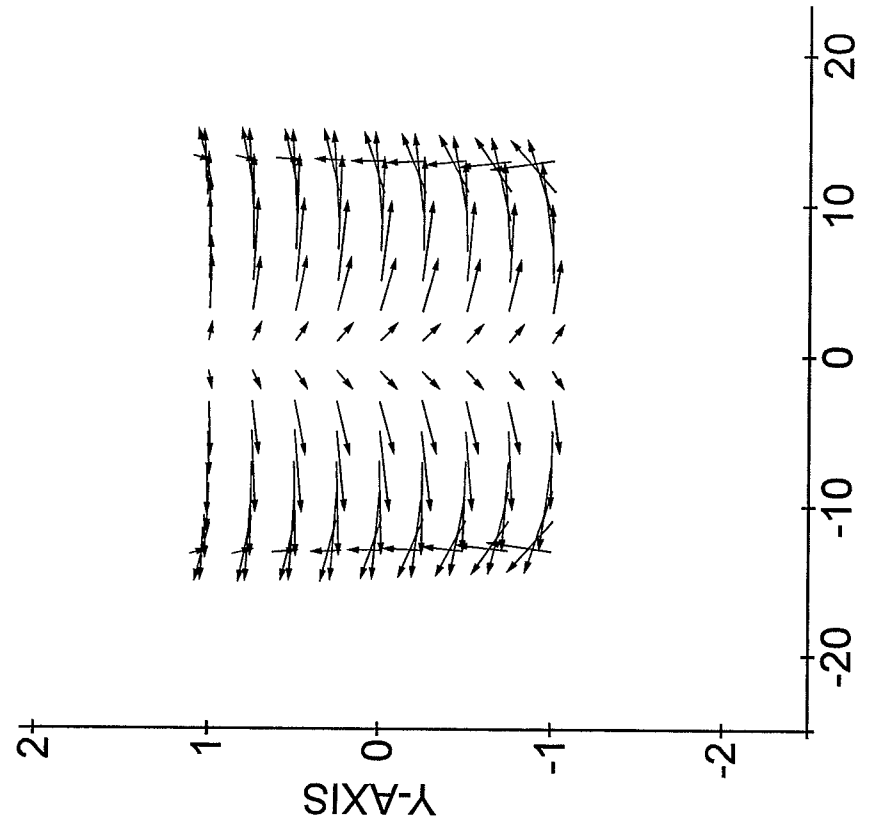


Fig. 16B

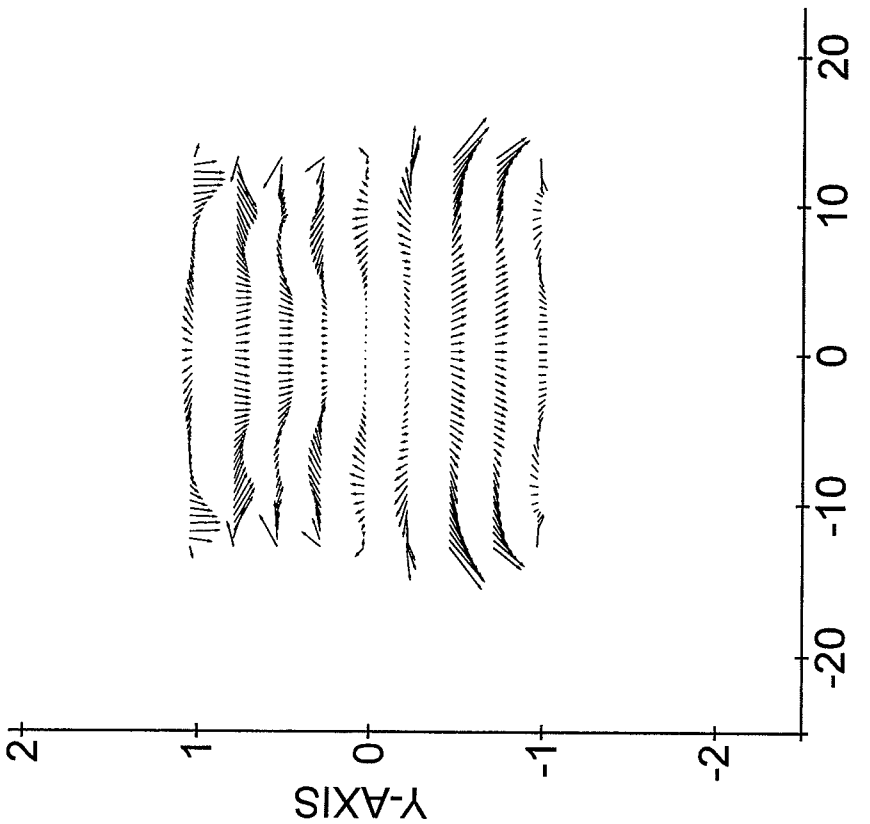


Fig. 16A

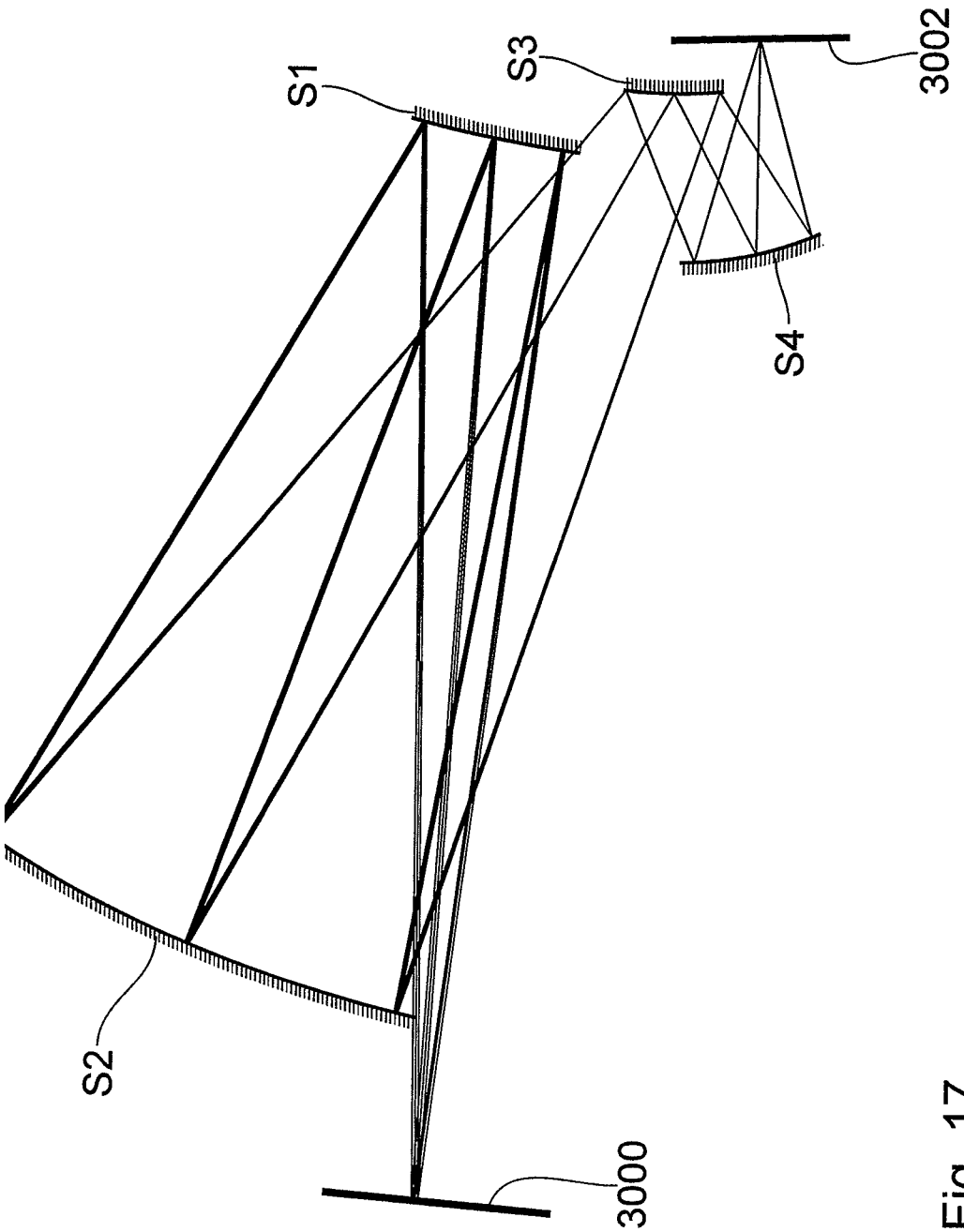
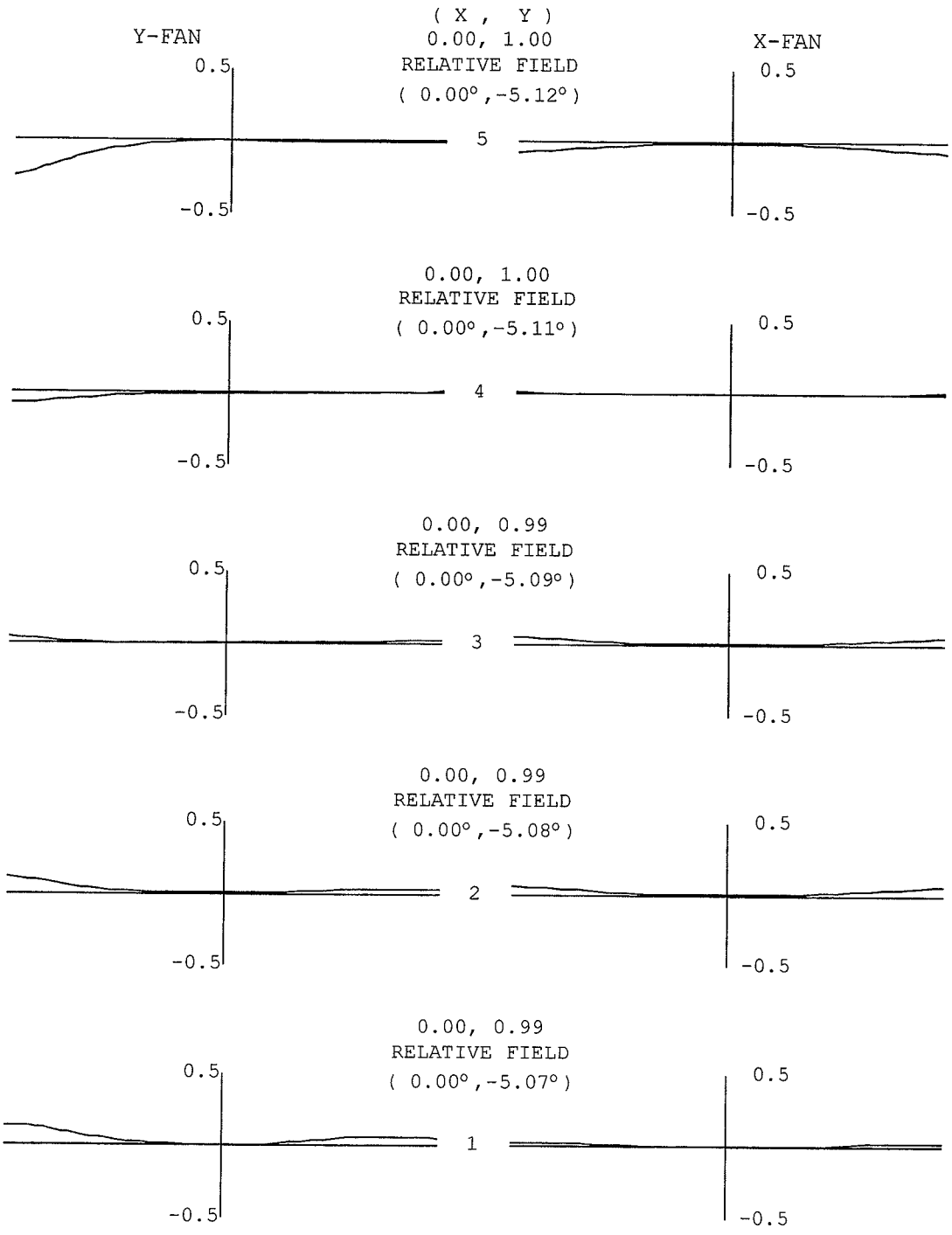


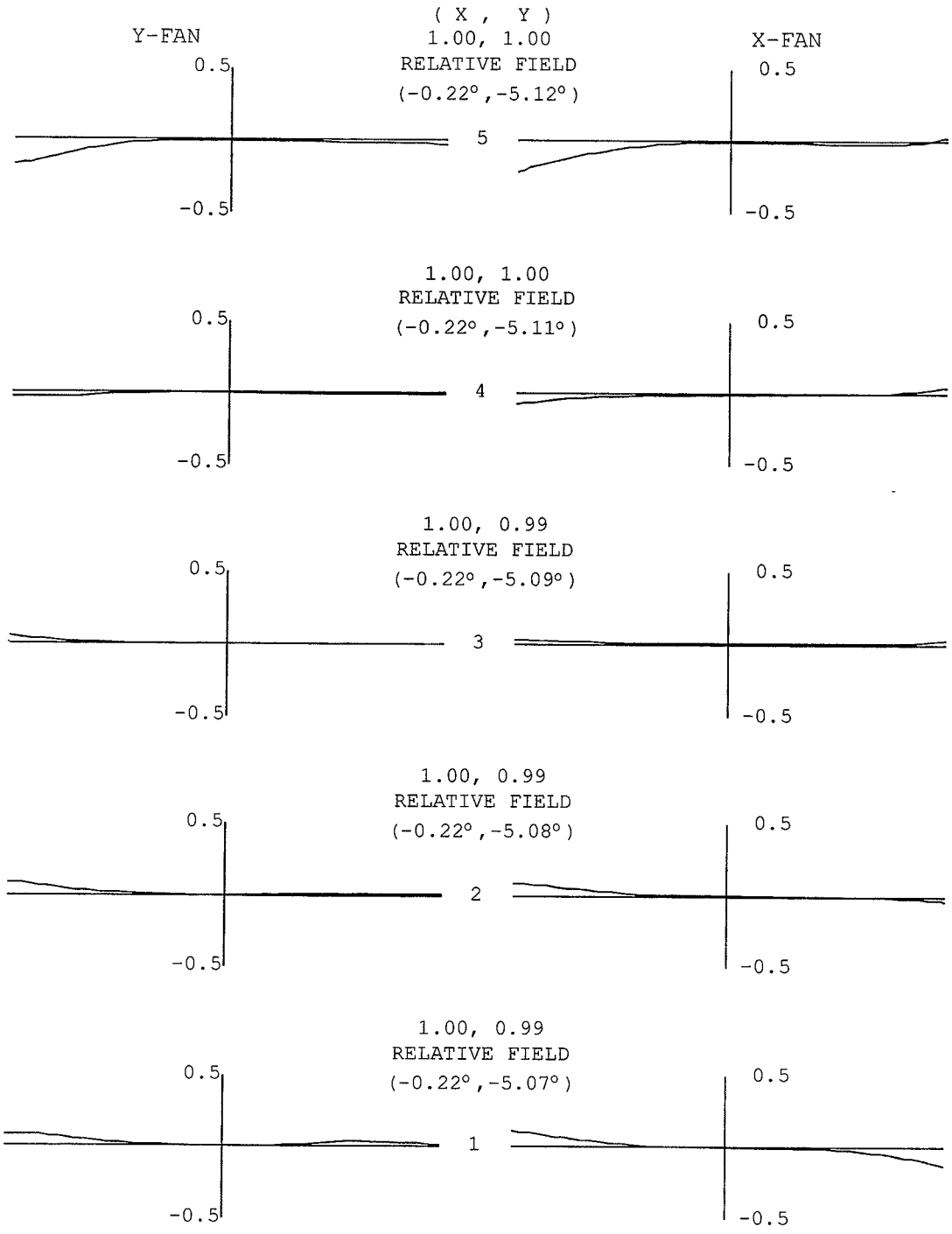
Fig. 17



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

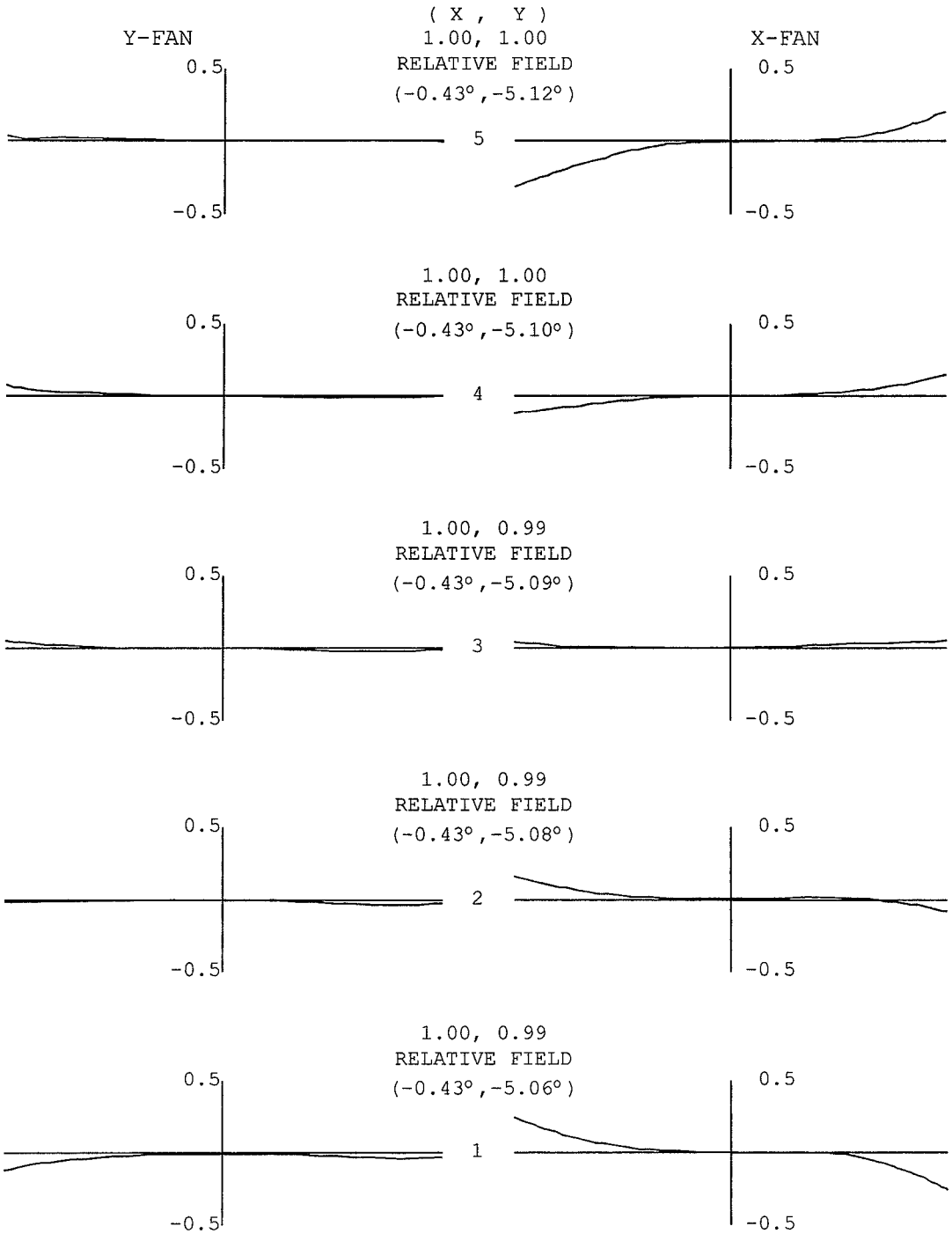
Fig. 18



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 19



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 20

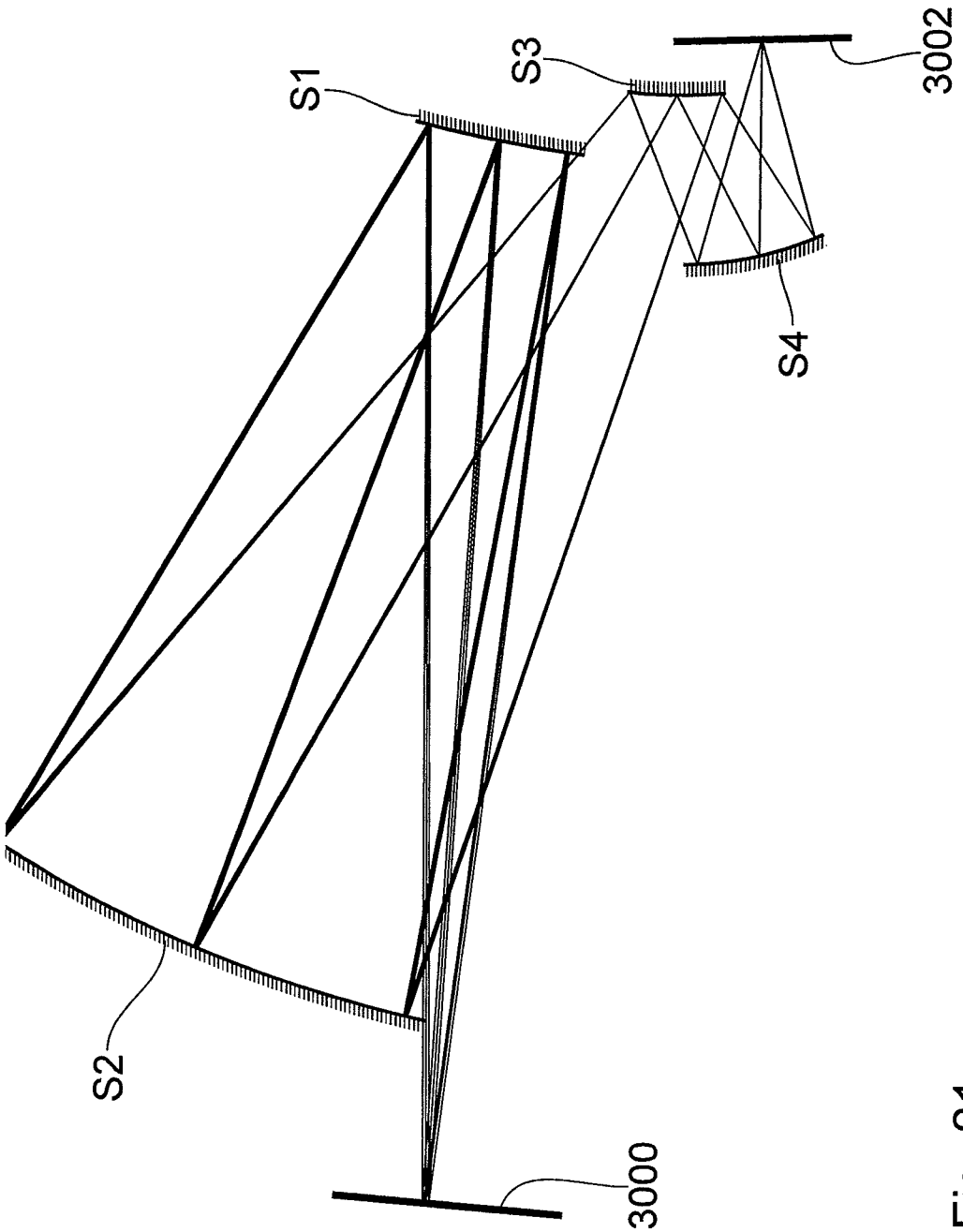
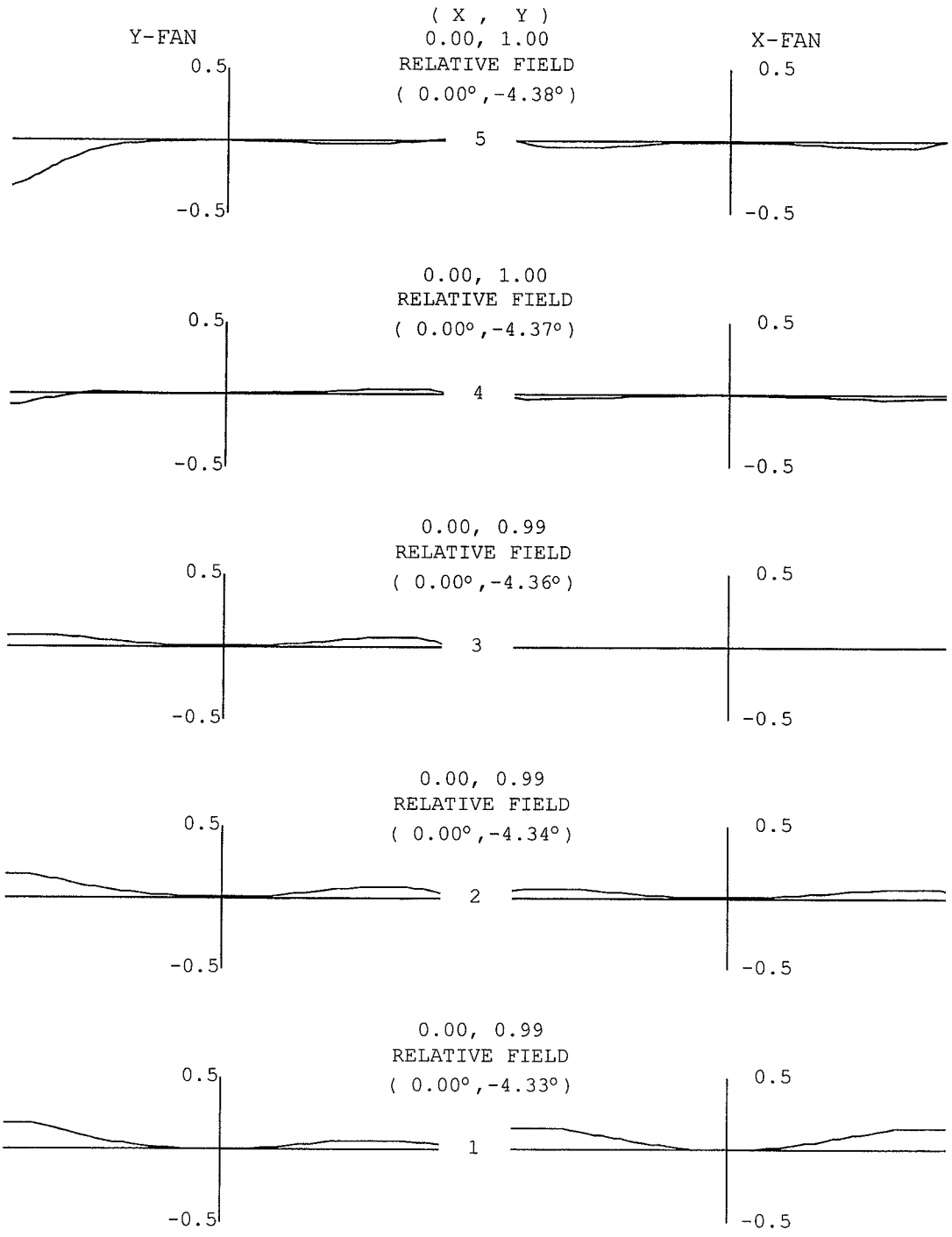


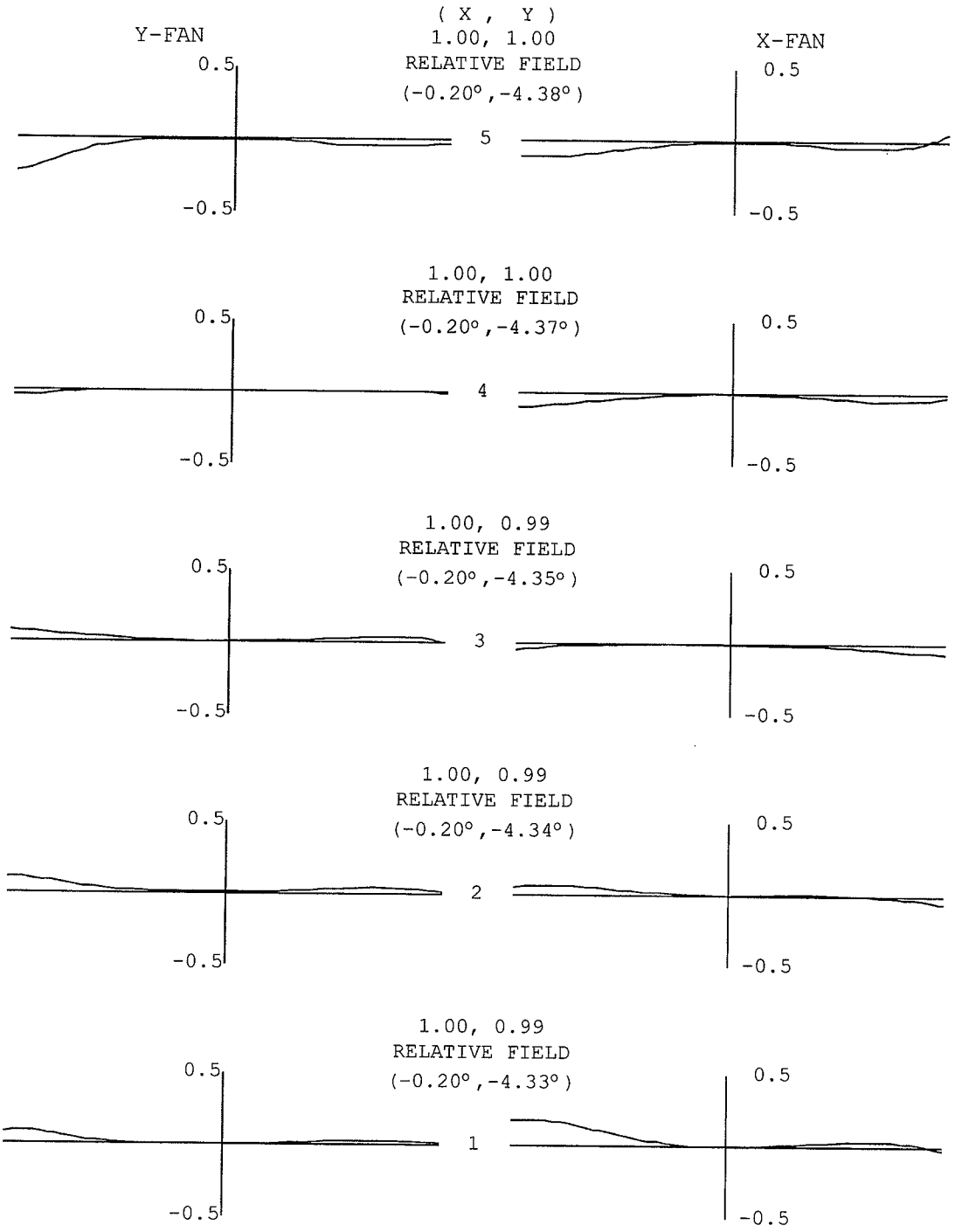
Fig. 21



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

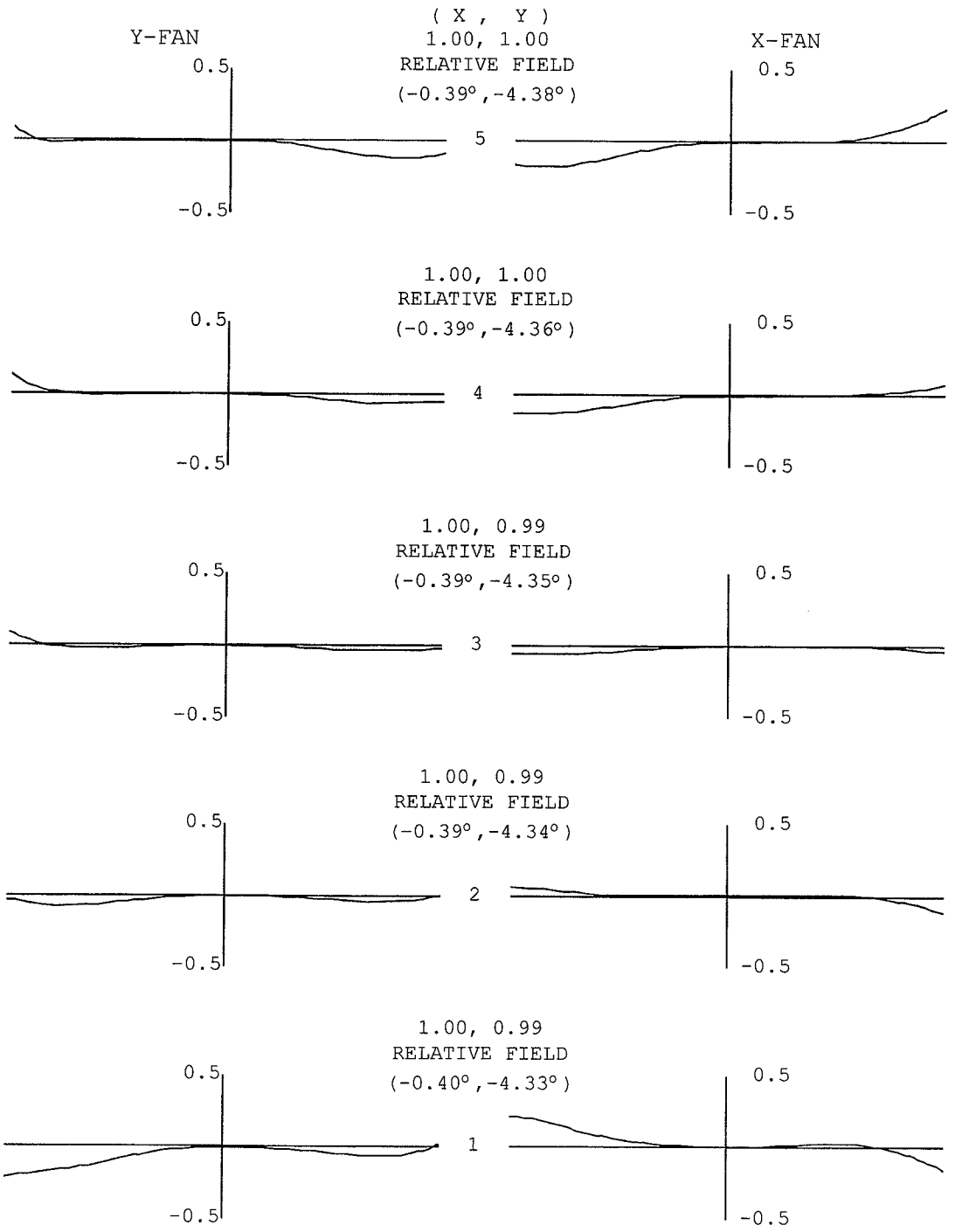
Fig. 22



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 23



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 24

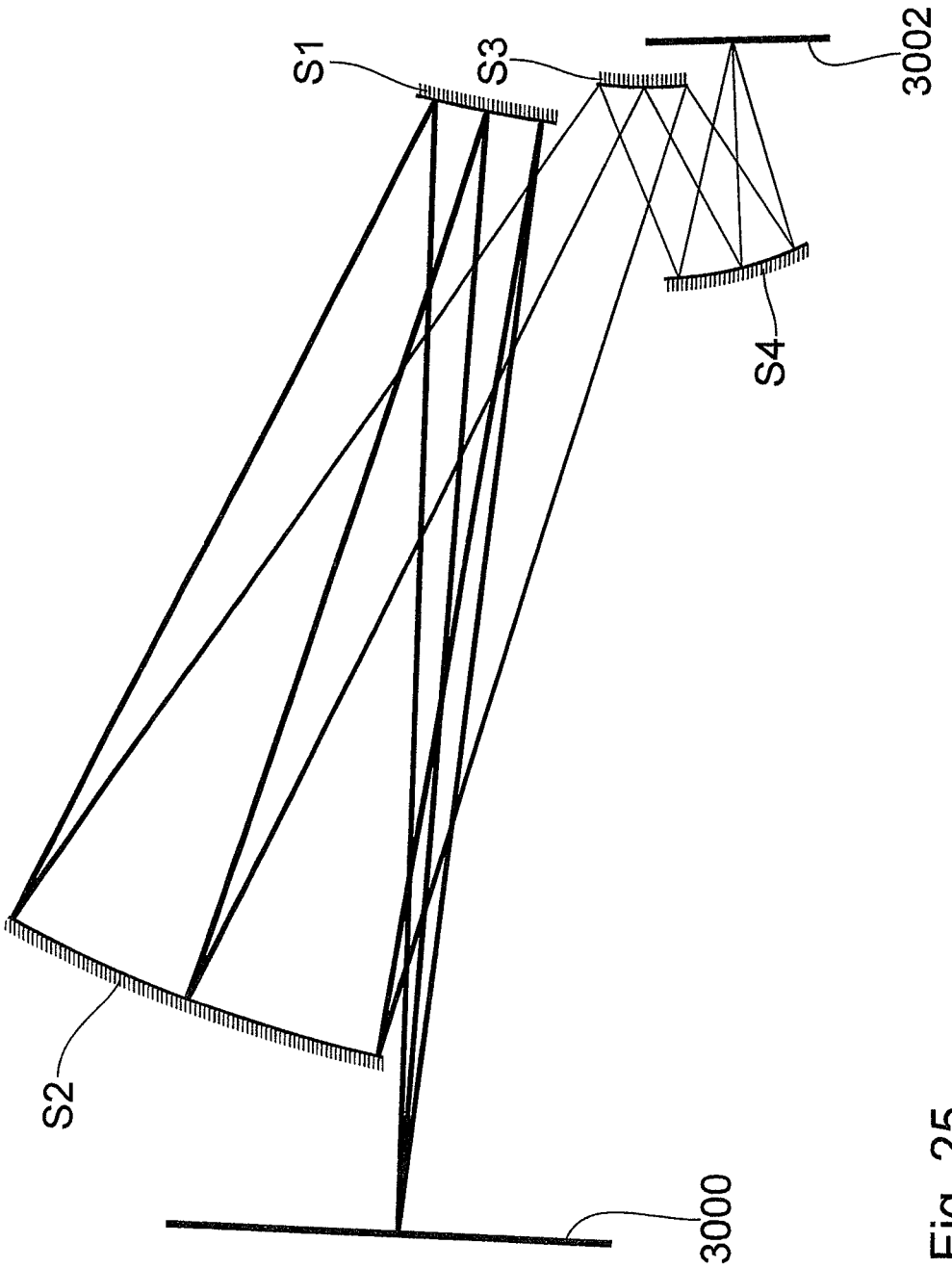
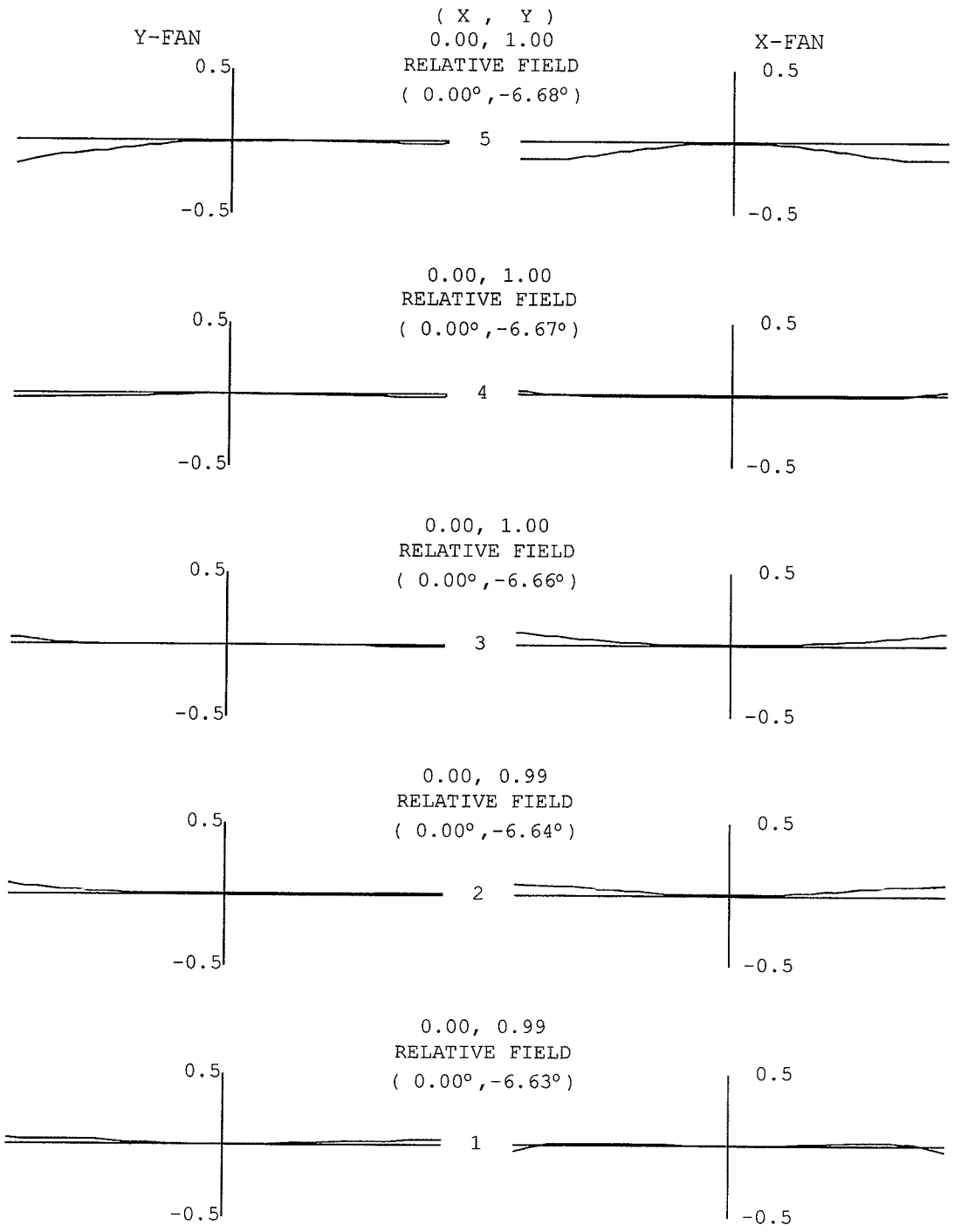


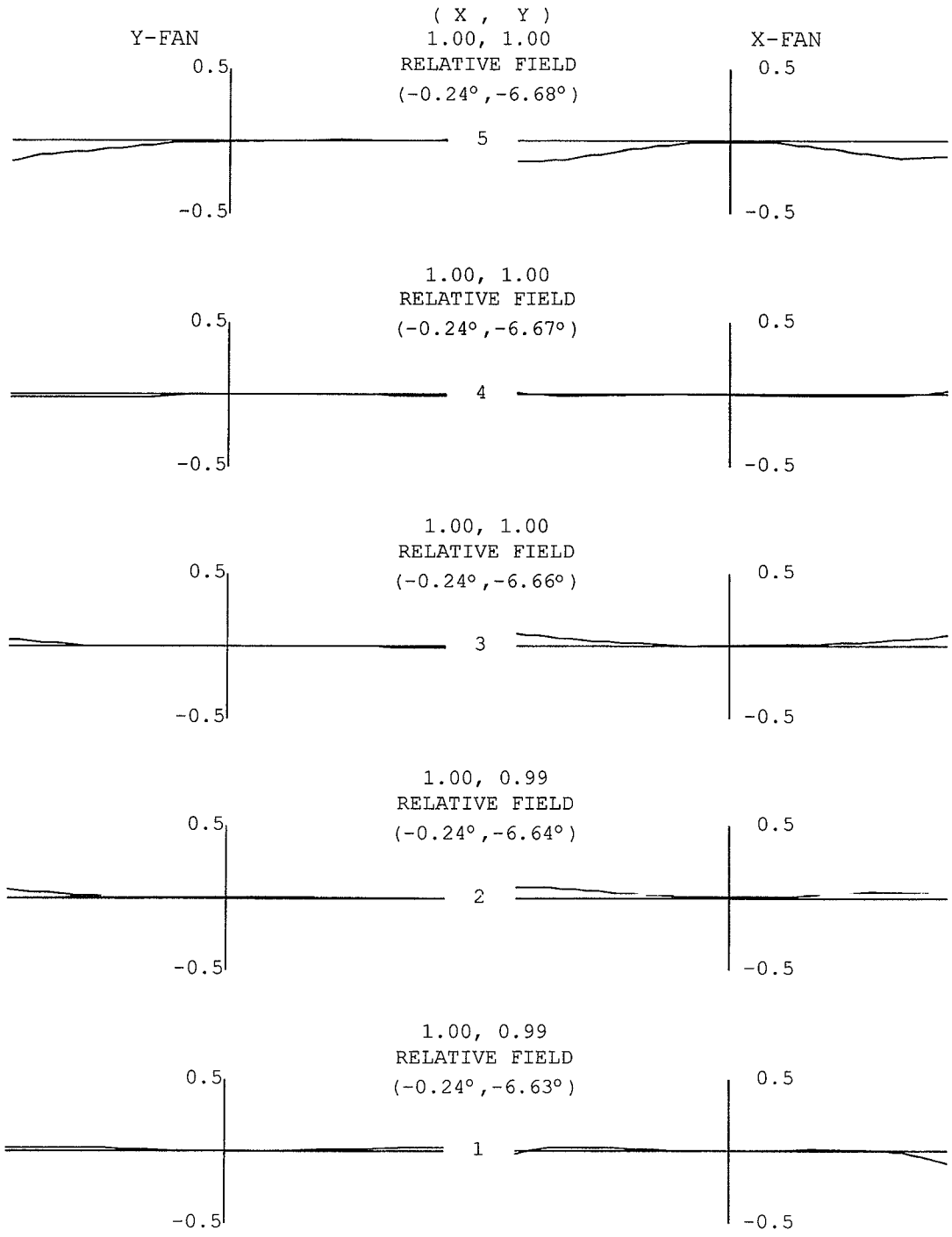
Fig. 25



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

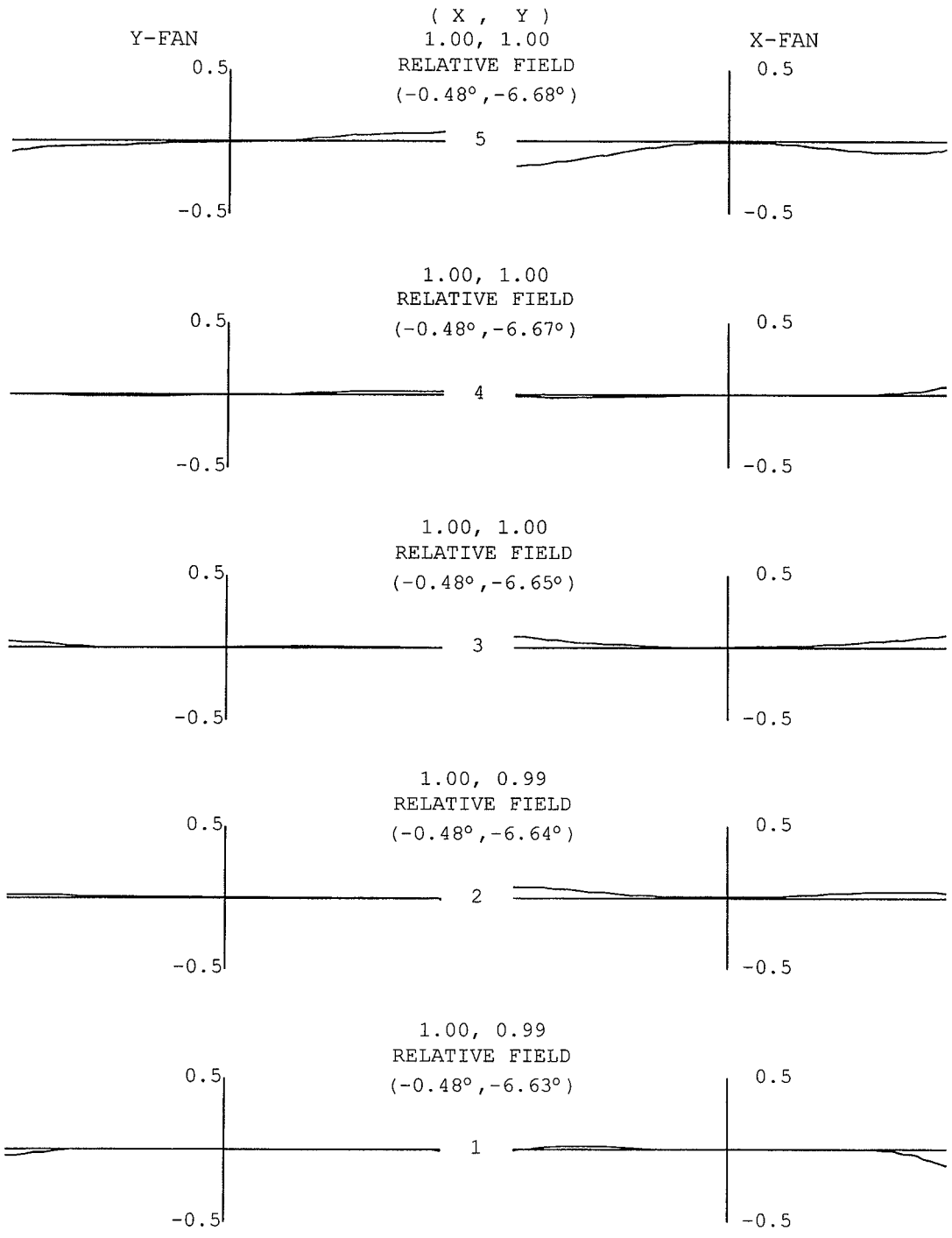
Fig. 26



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 27



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 28

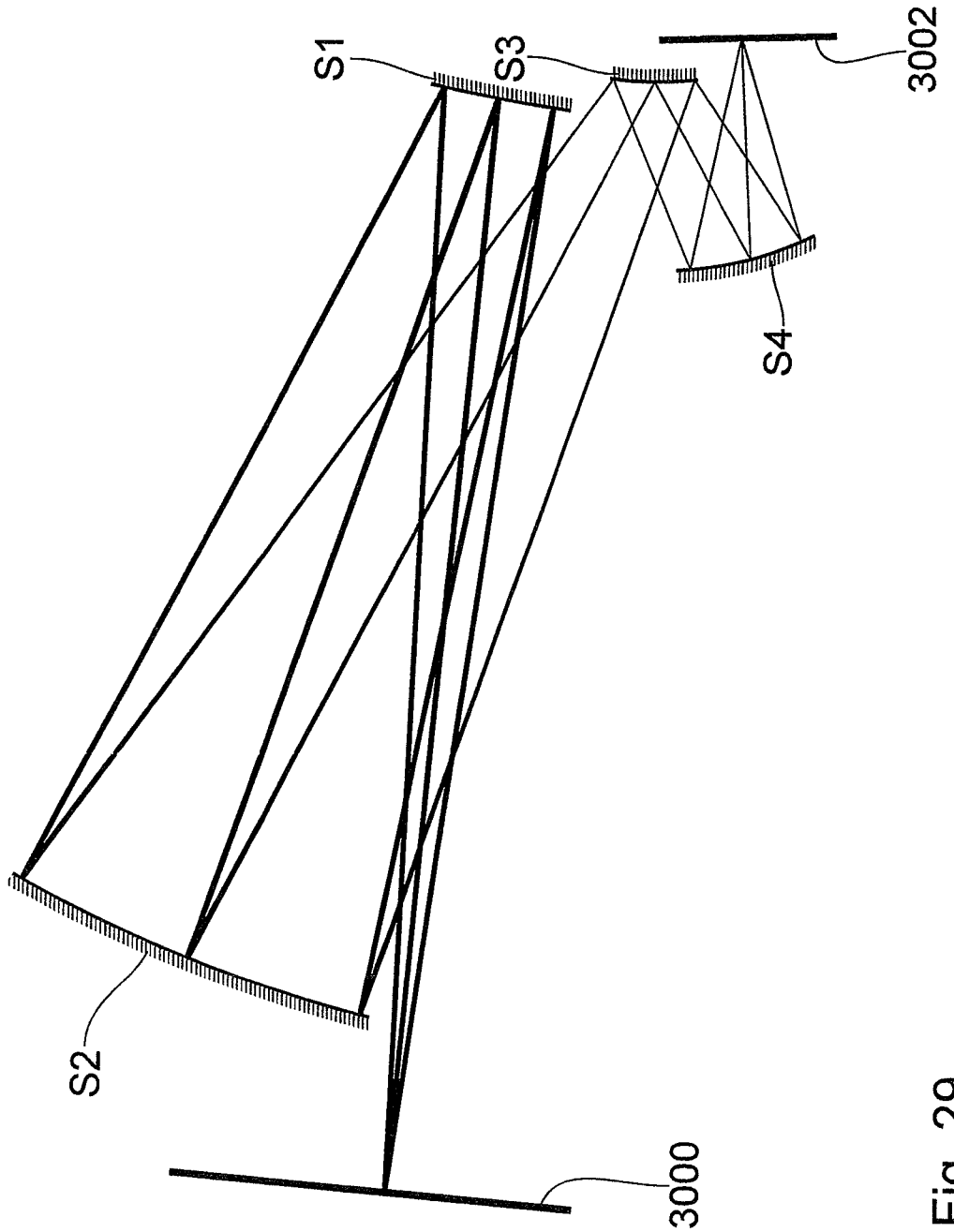
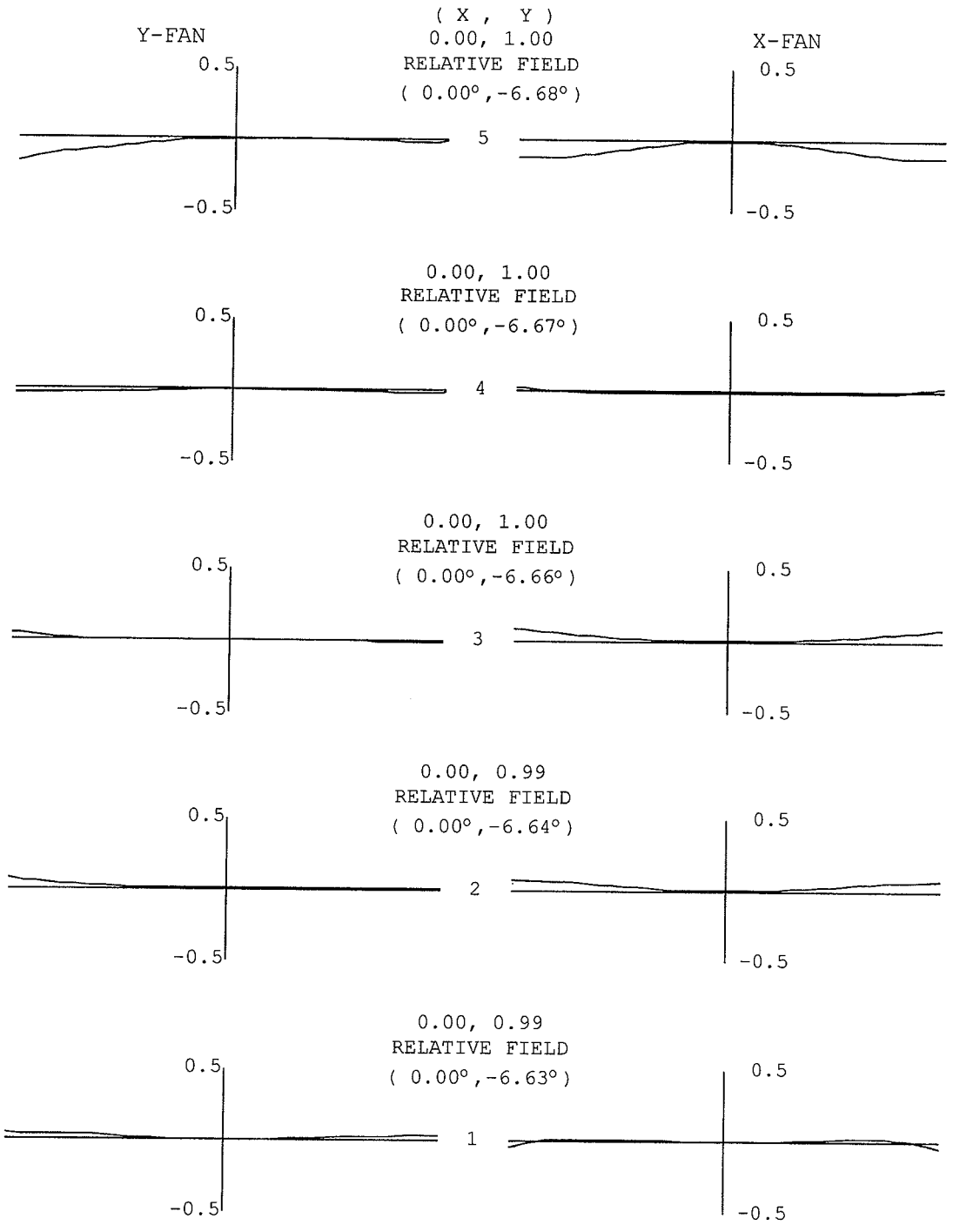


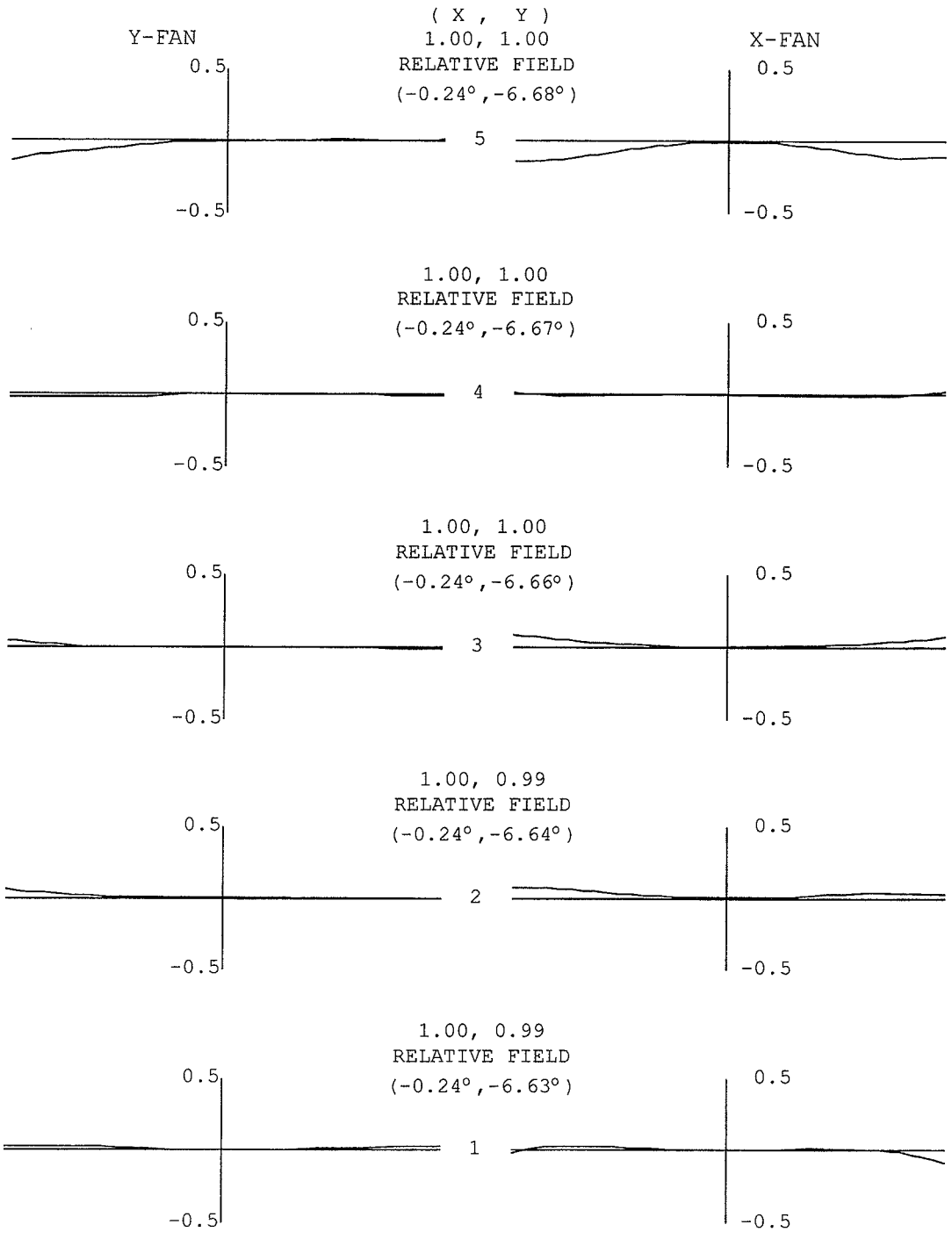
Fig. 29



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

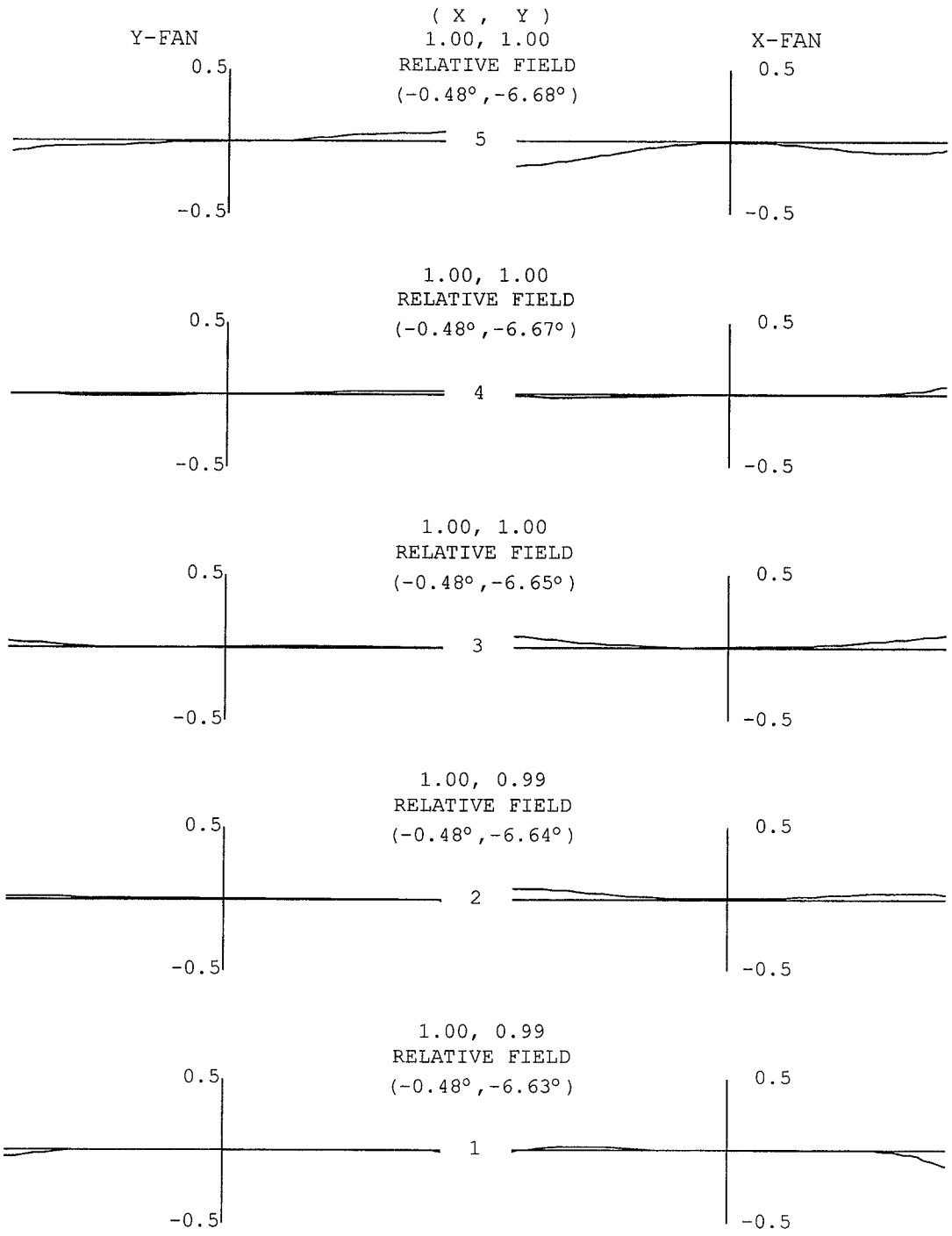
Fig. 30



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 31



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 32

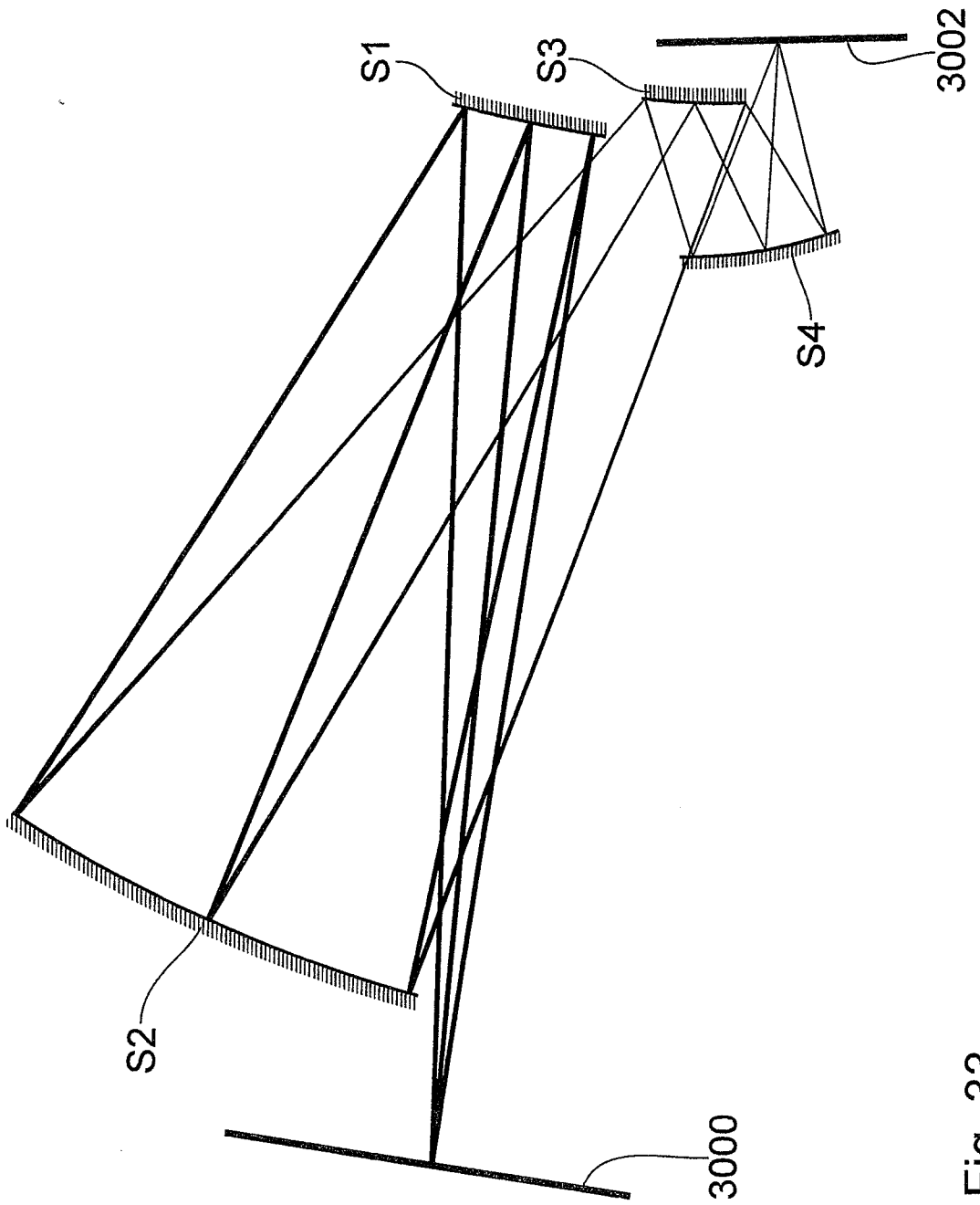
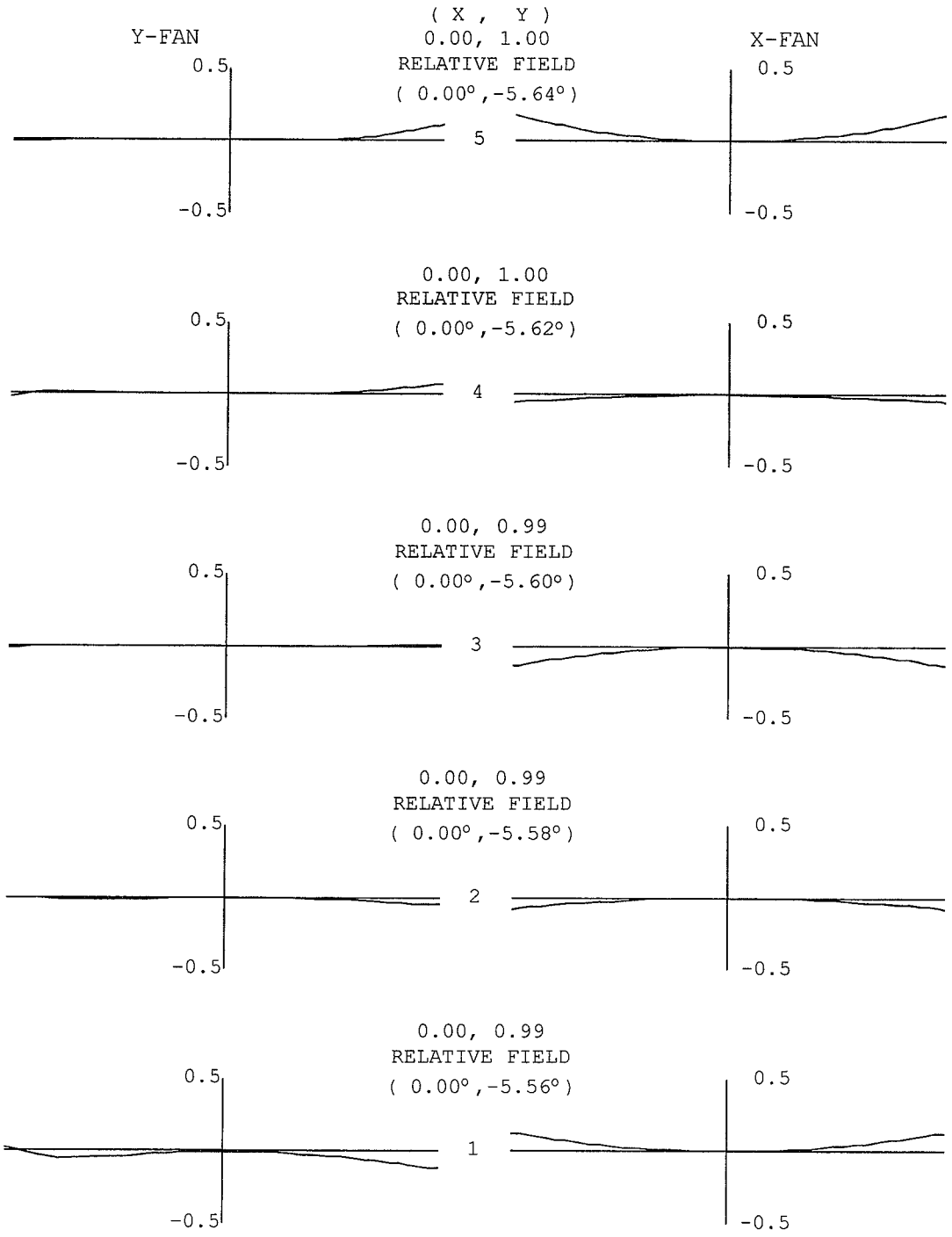


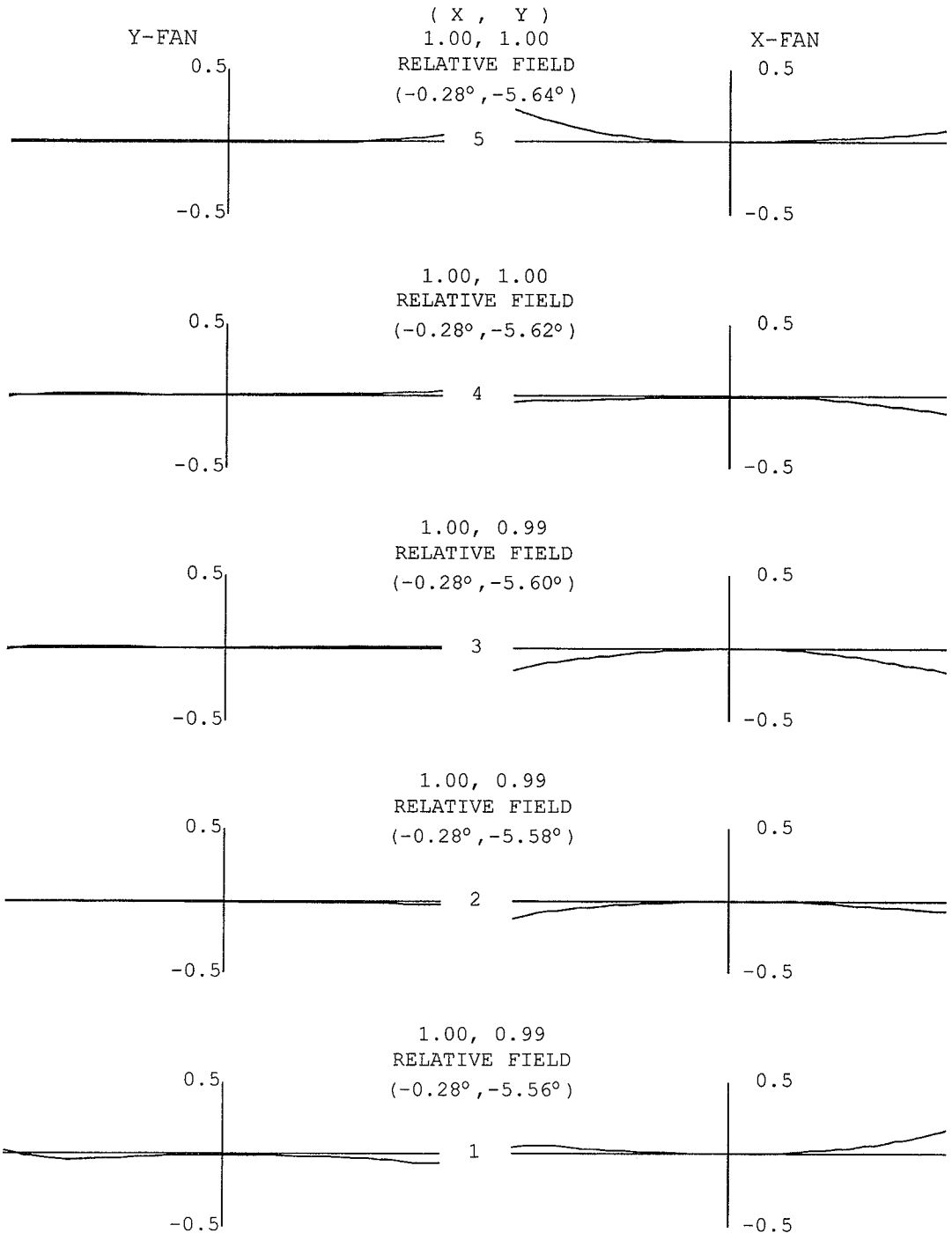
Fig. 33



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

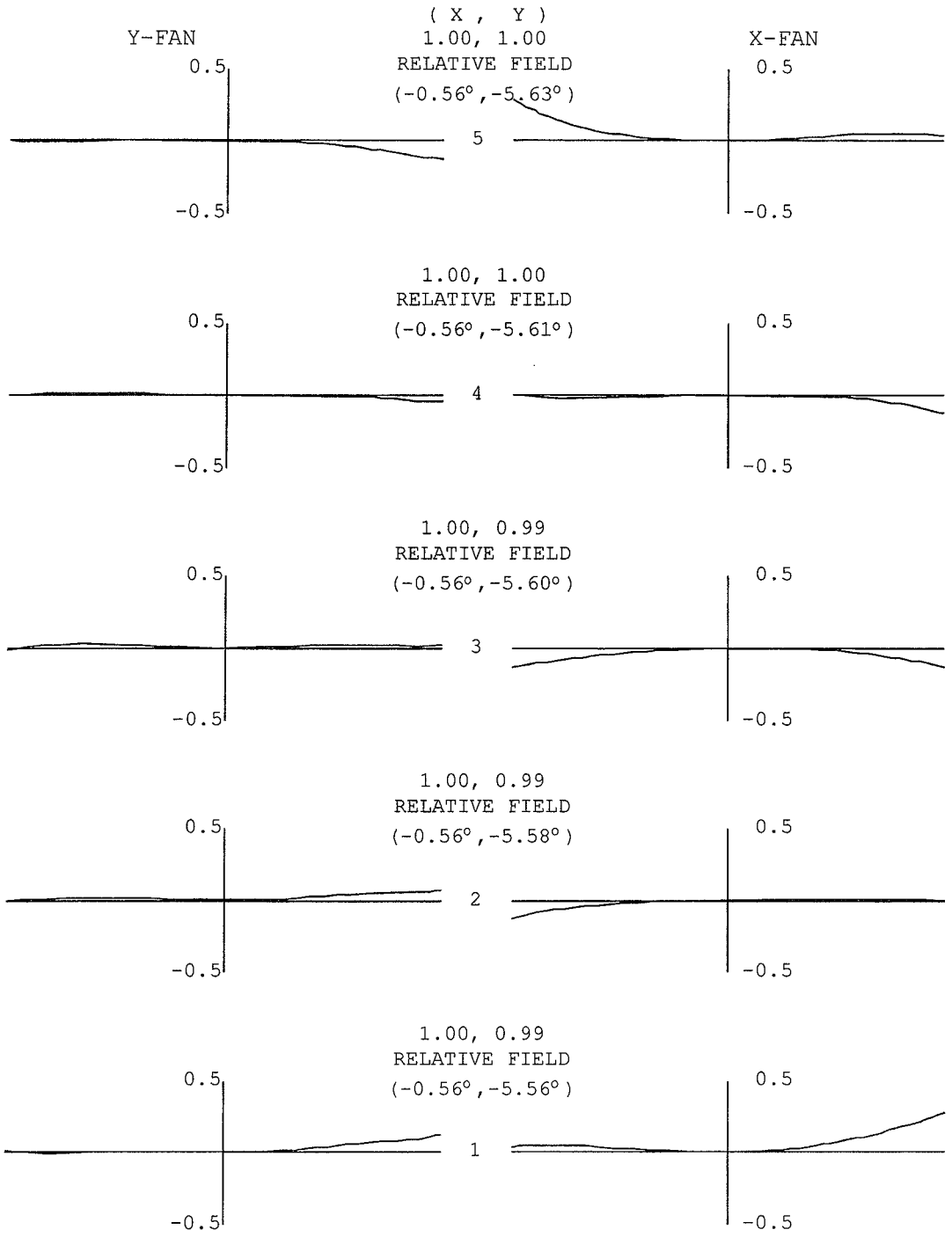
Fig. 34



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 35



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 36

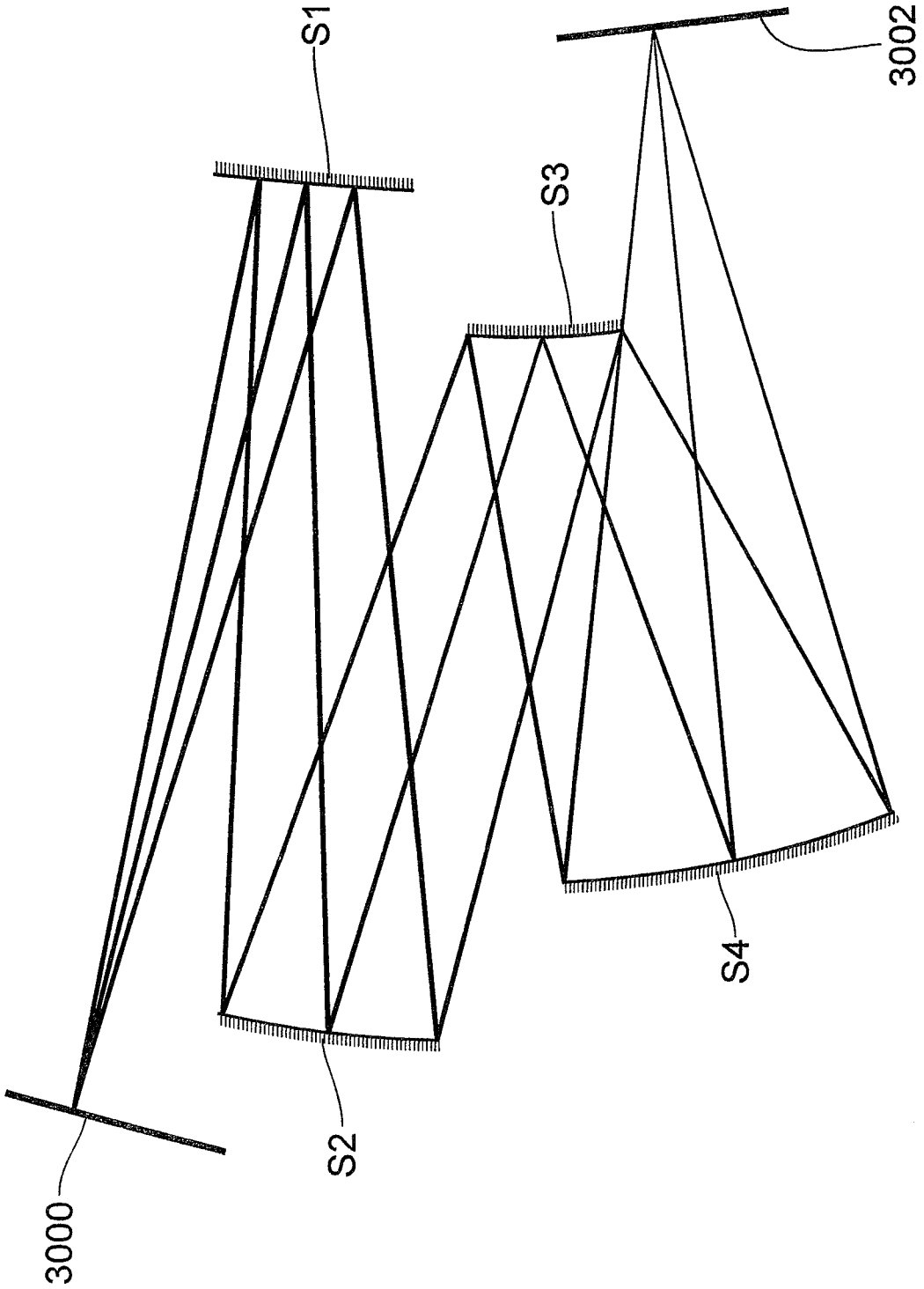
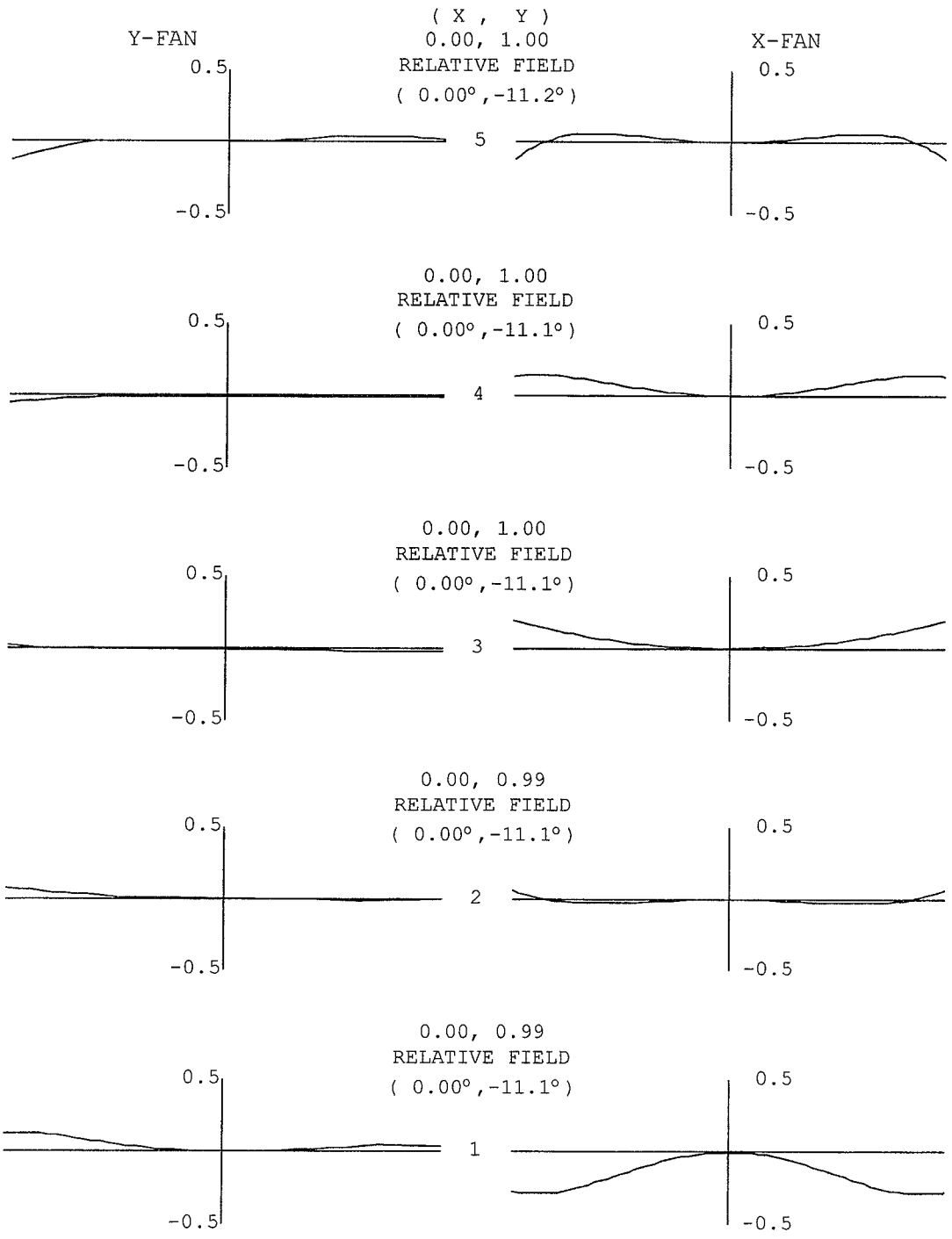


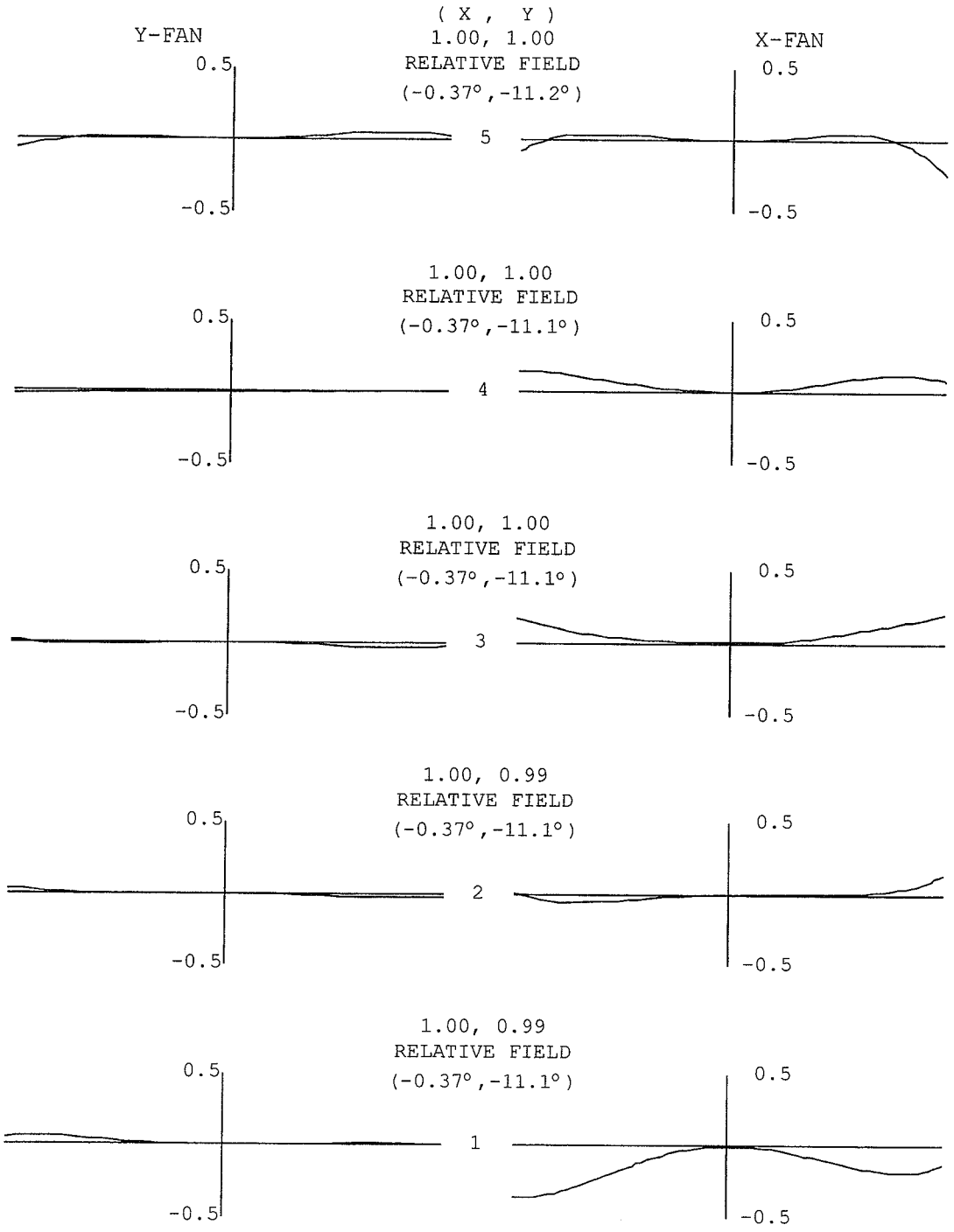
Fig. 37



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

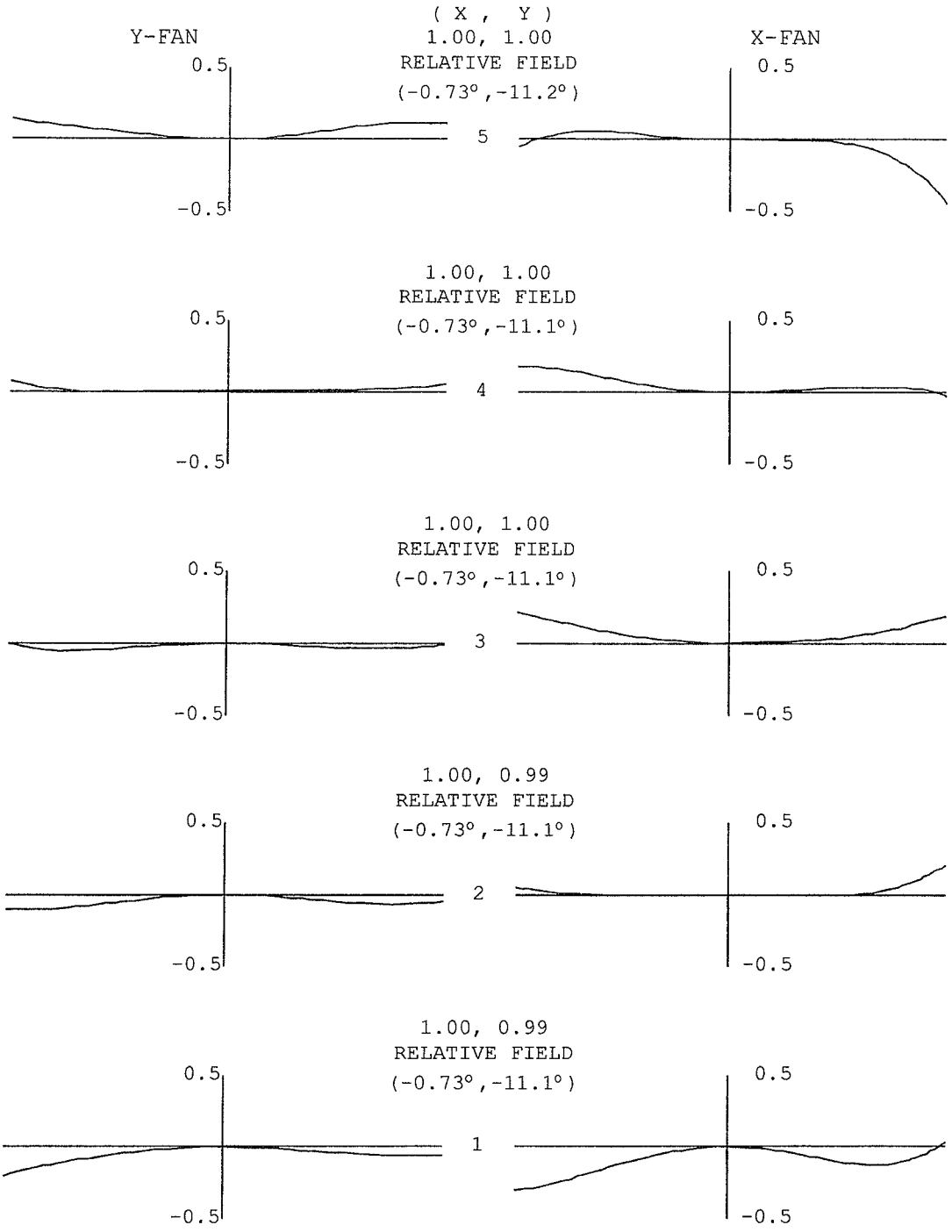
Fig. 38



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 39



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 40

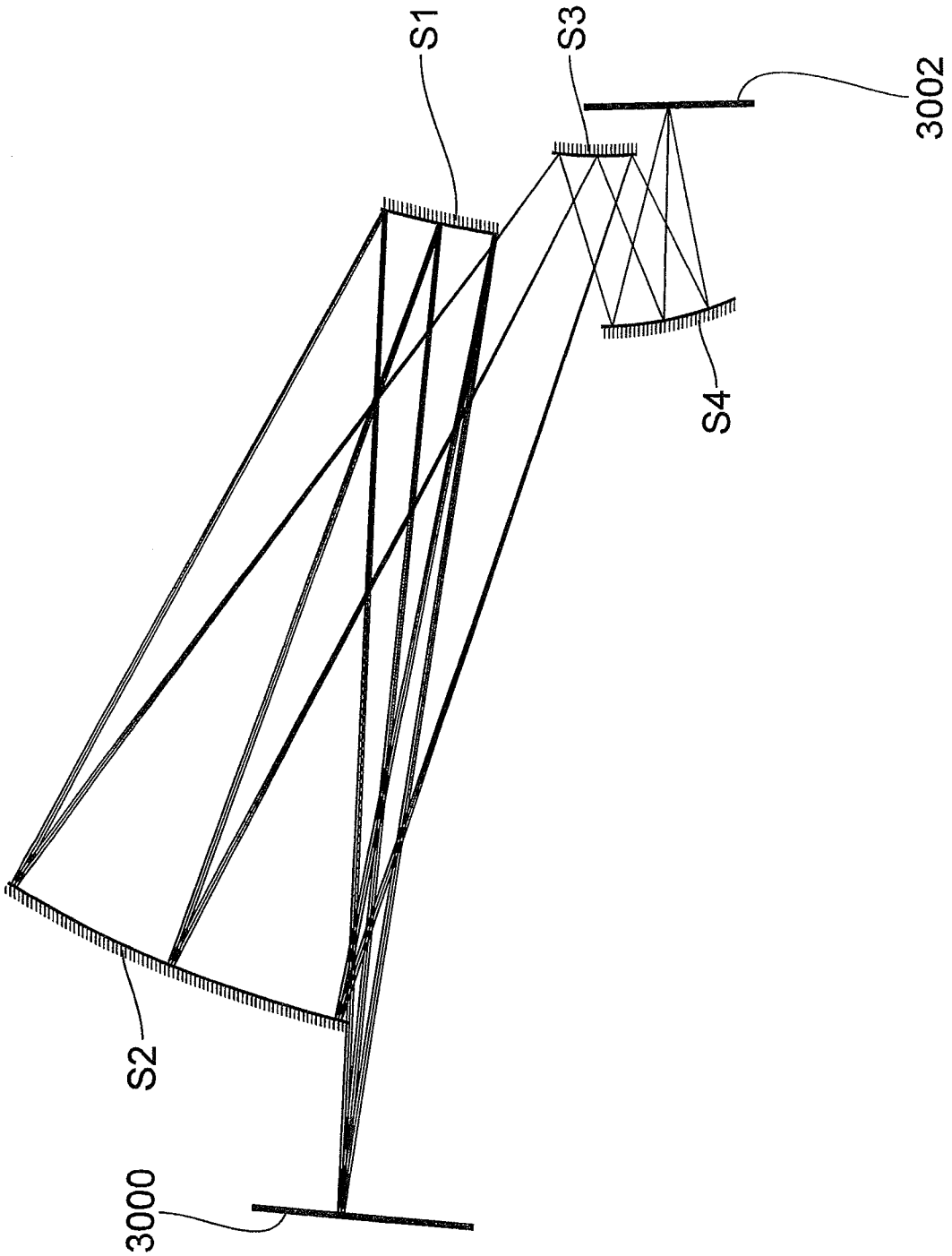
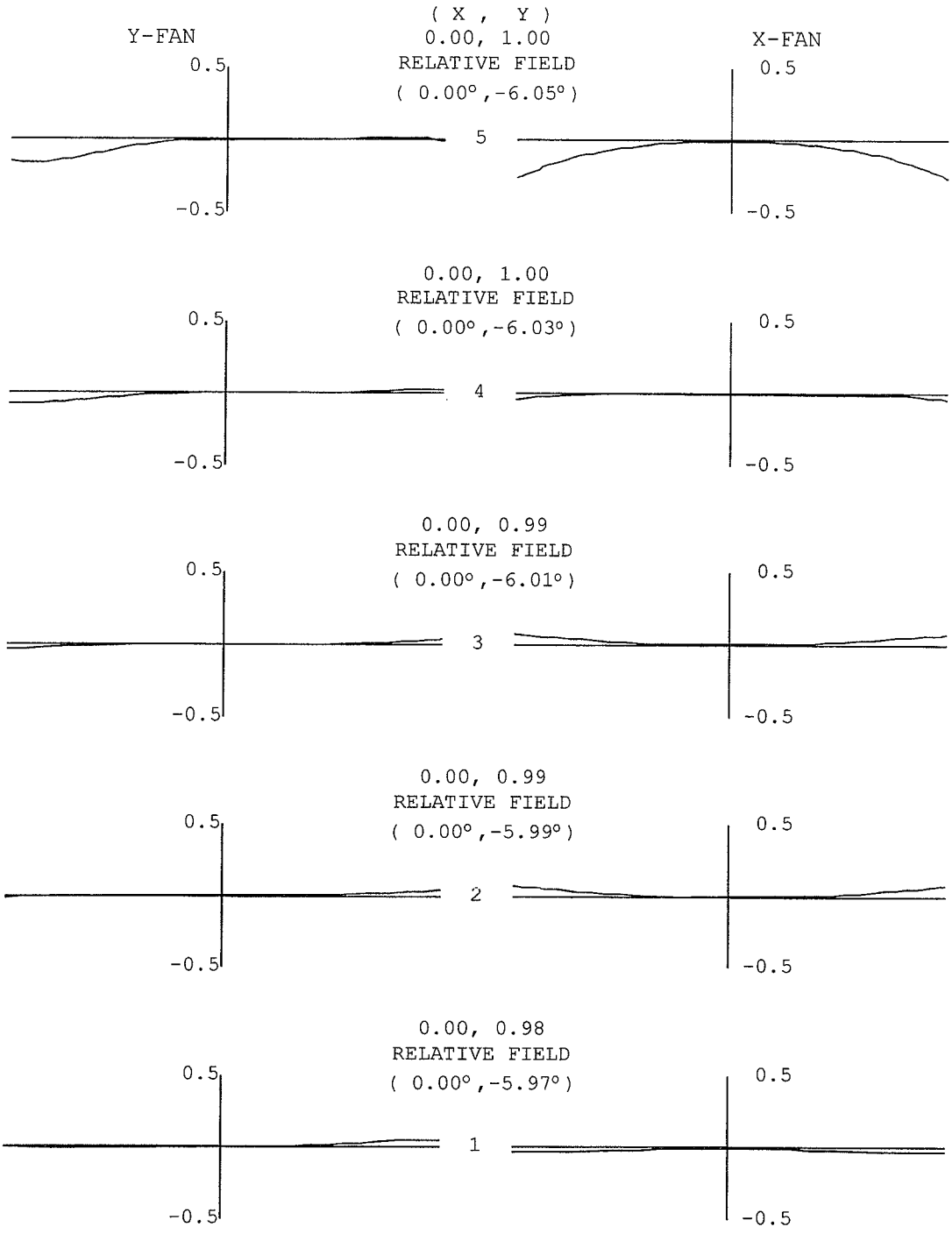


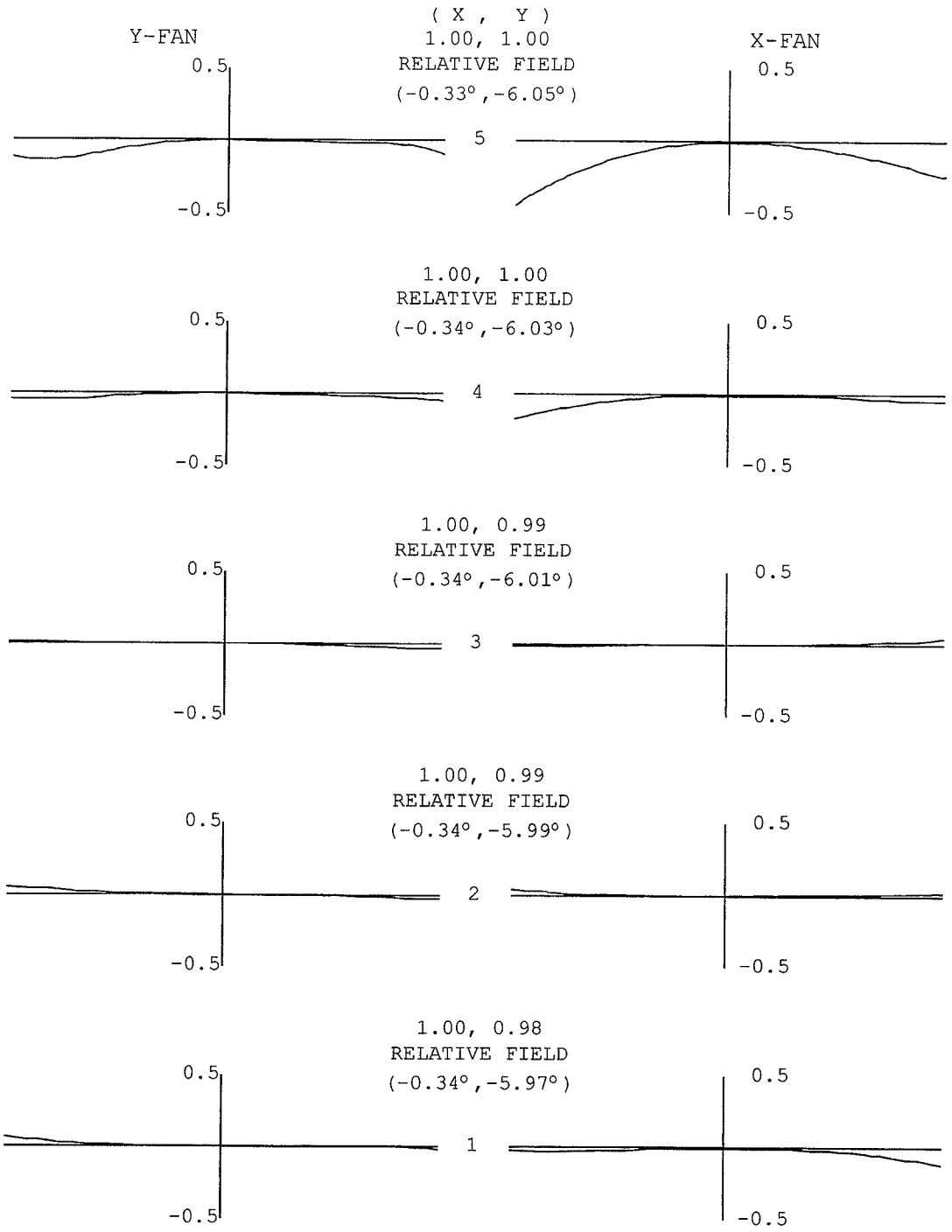
Fig. 41



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

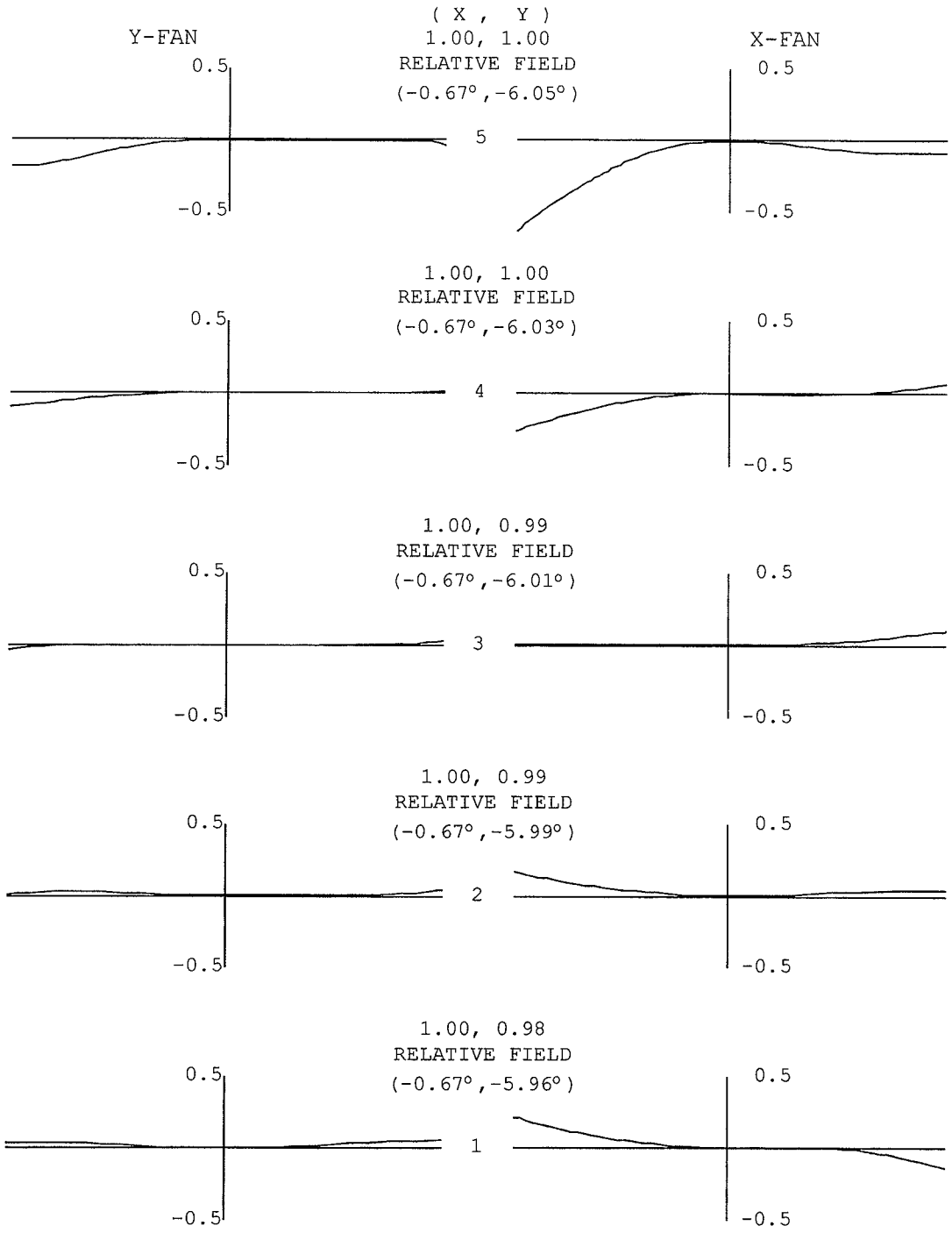
Fig. 42



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 43



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 44

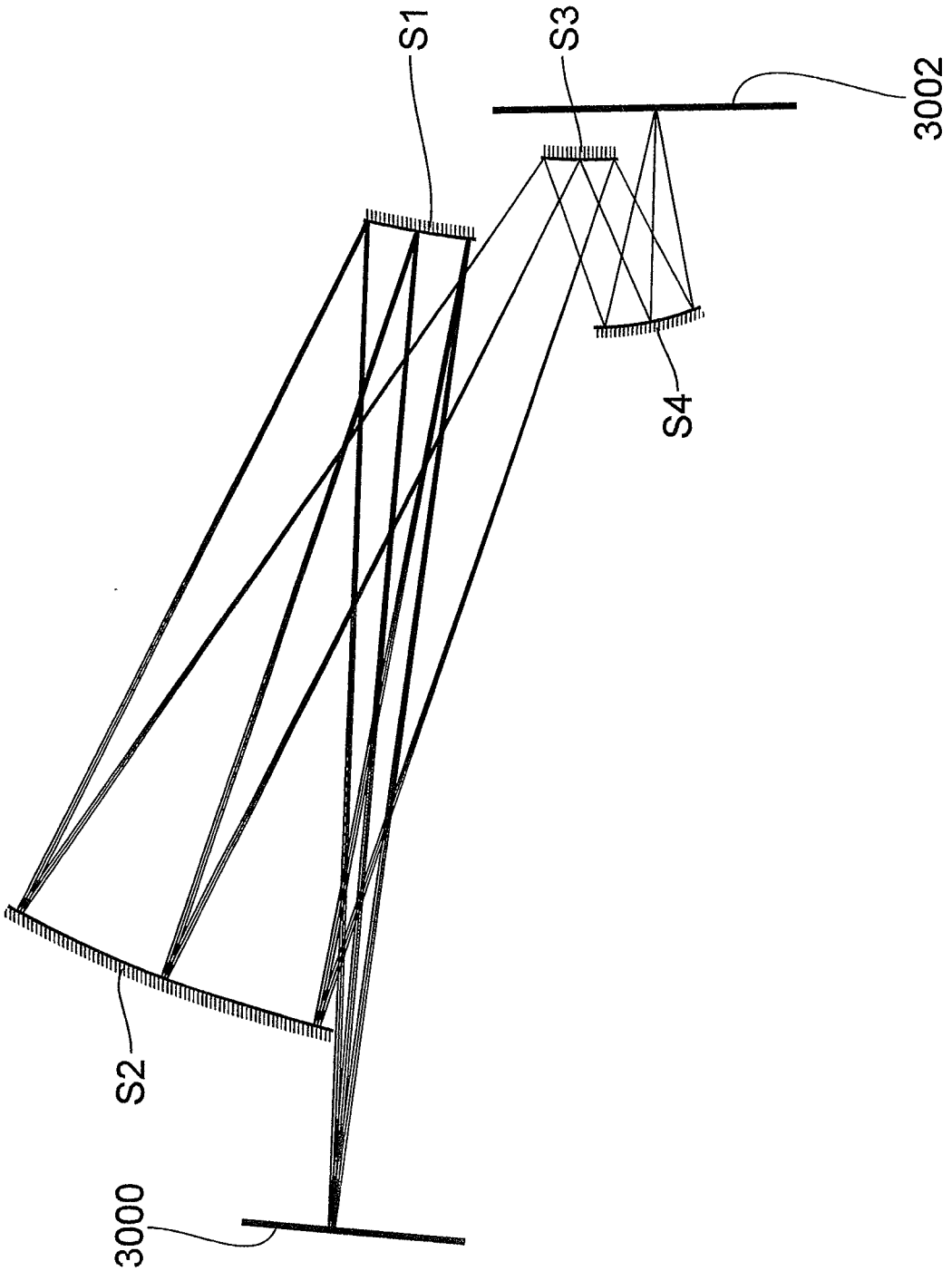
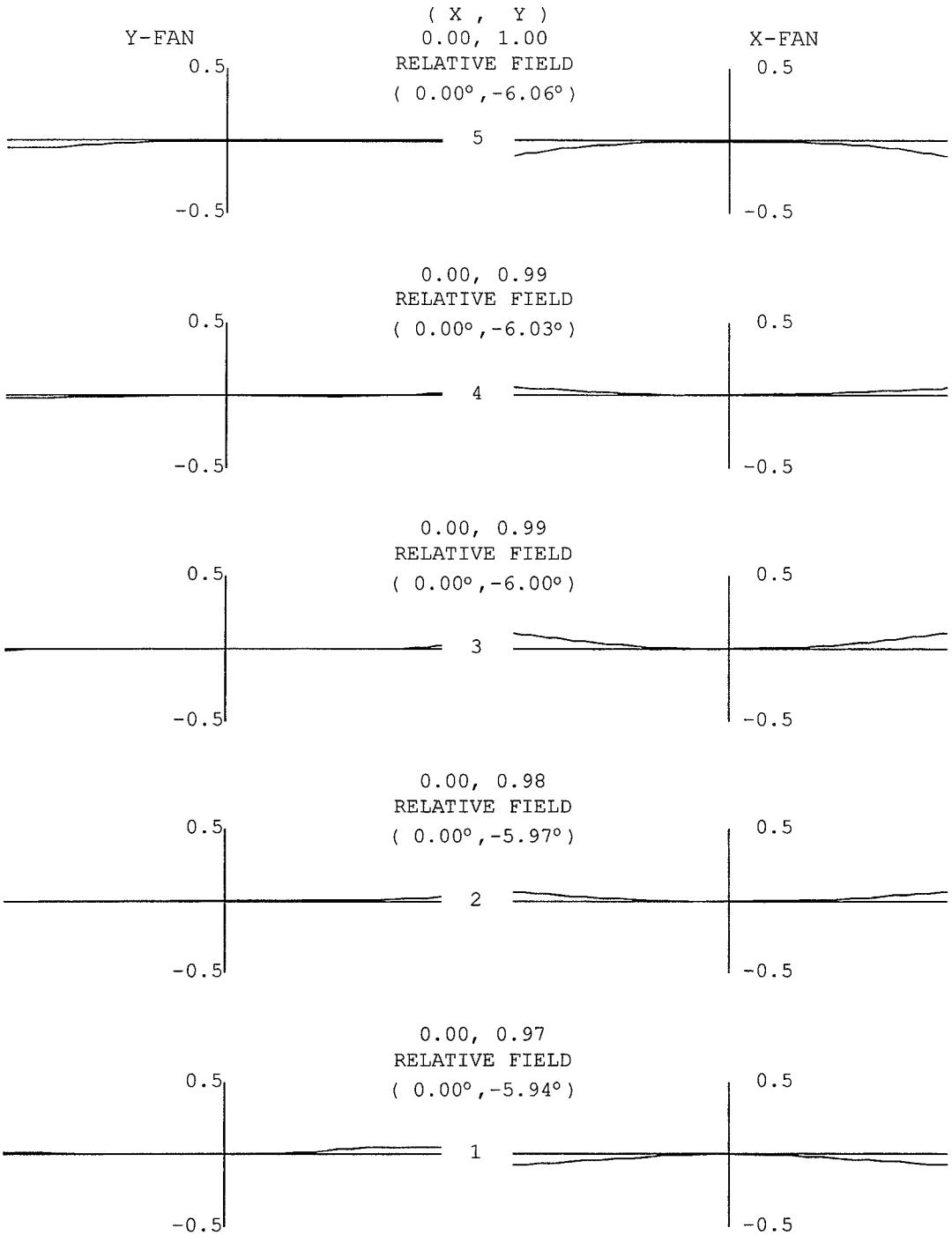


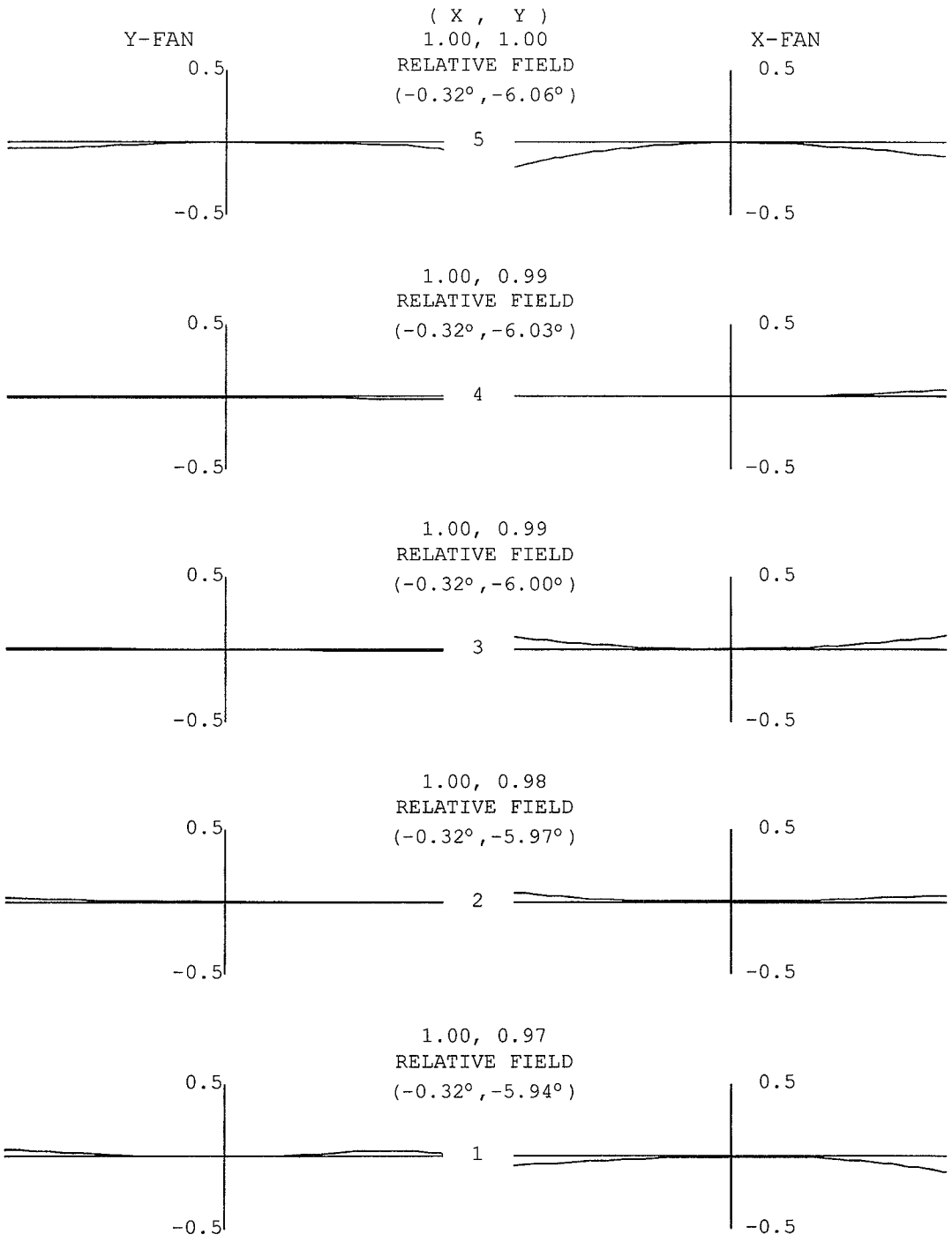
Fig. 45



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

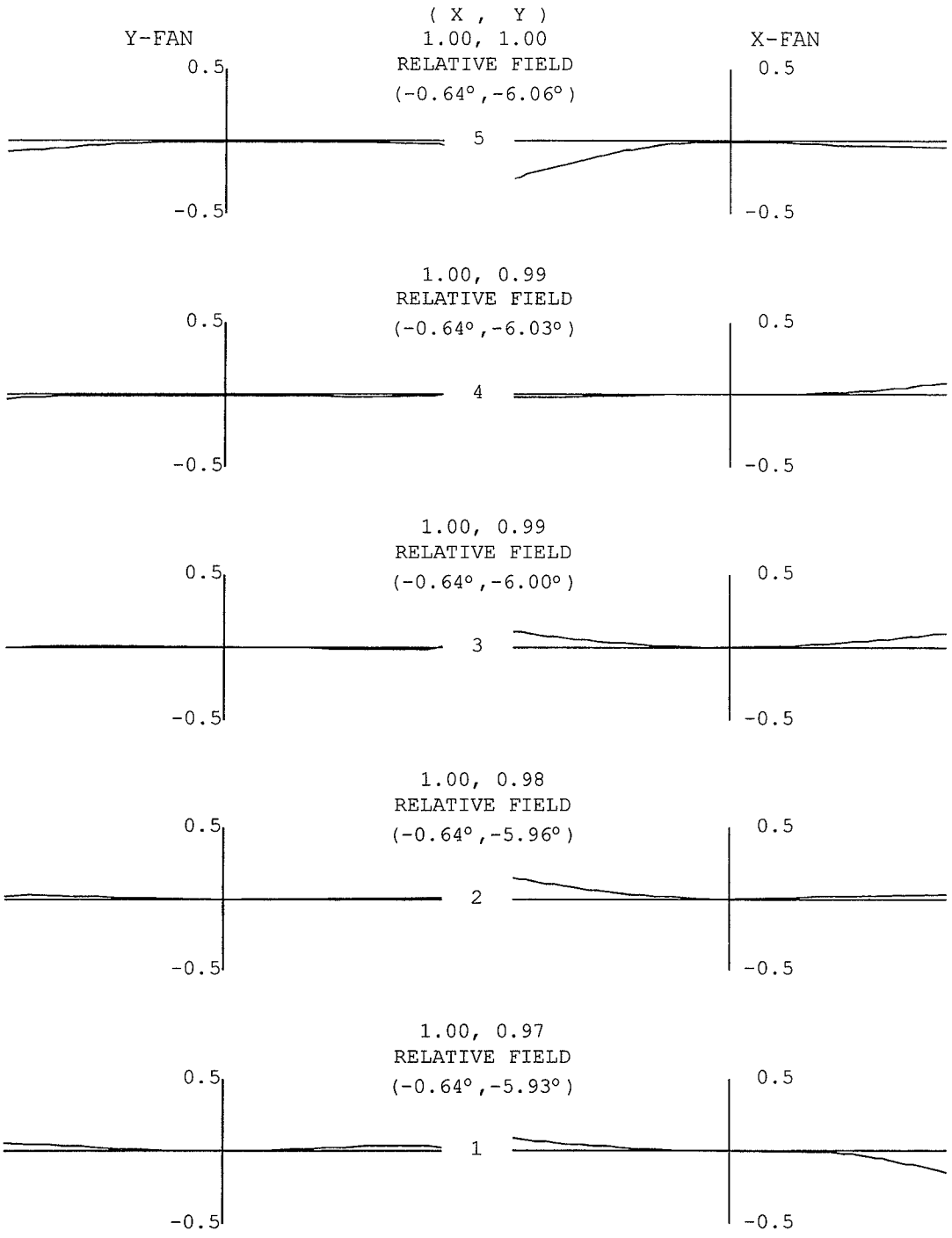
Fig. 46



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 47



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 48

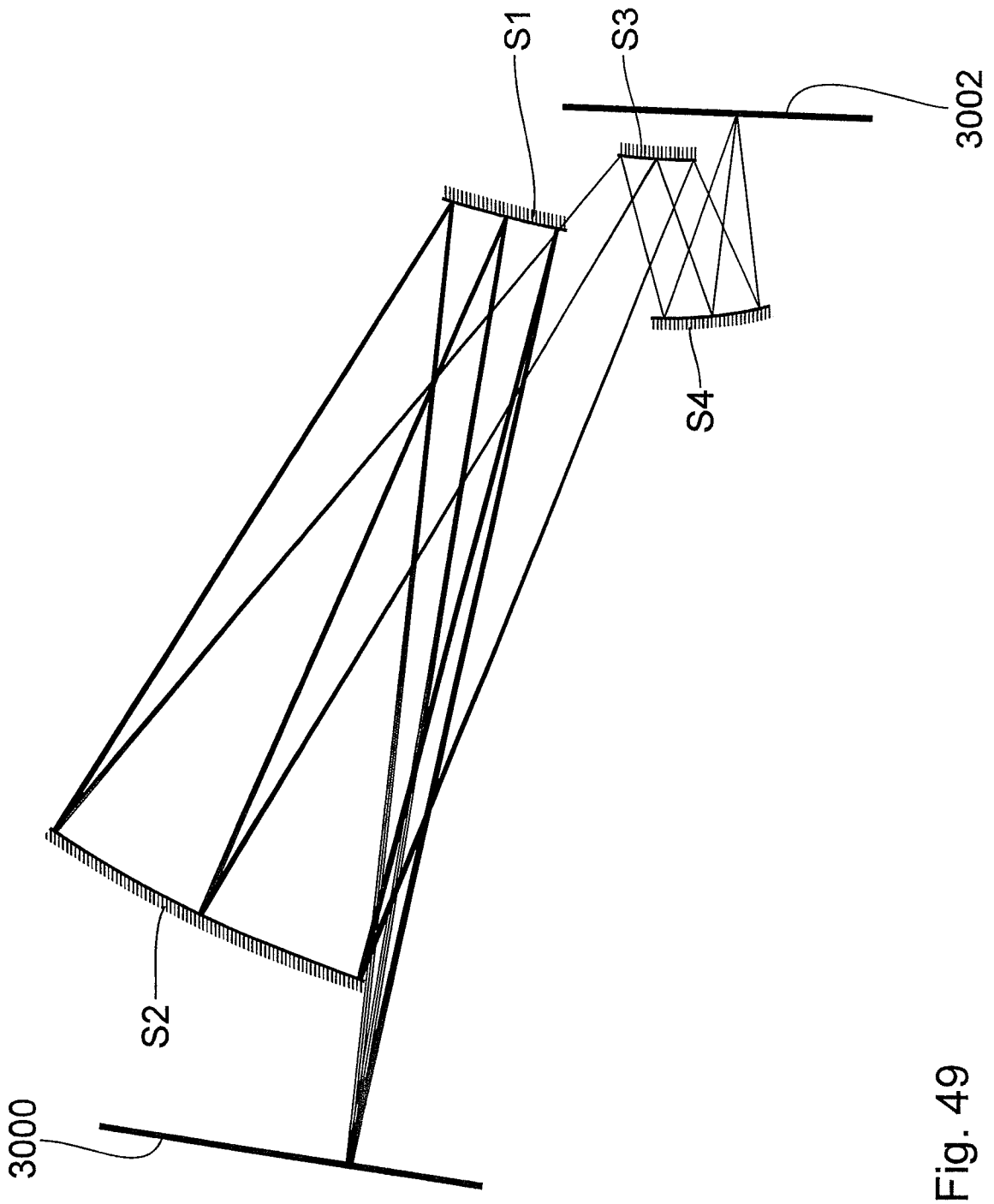
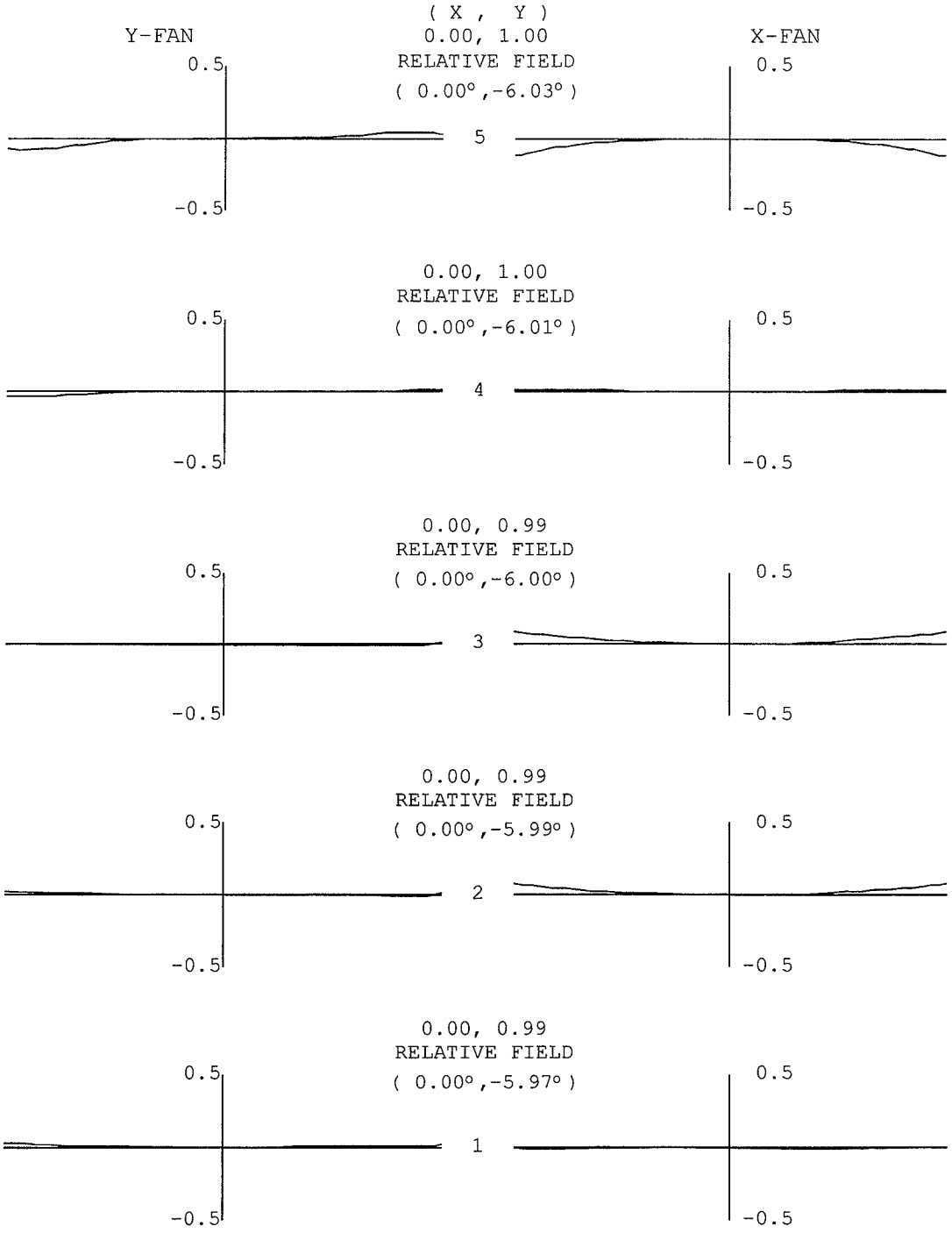


Fig. 49



13.5000 NM

OPTICAL PATH DIFFERENCE (WAVES)

Fig. 50

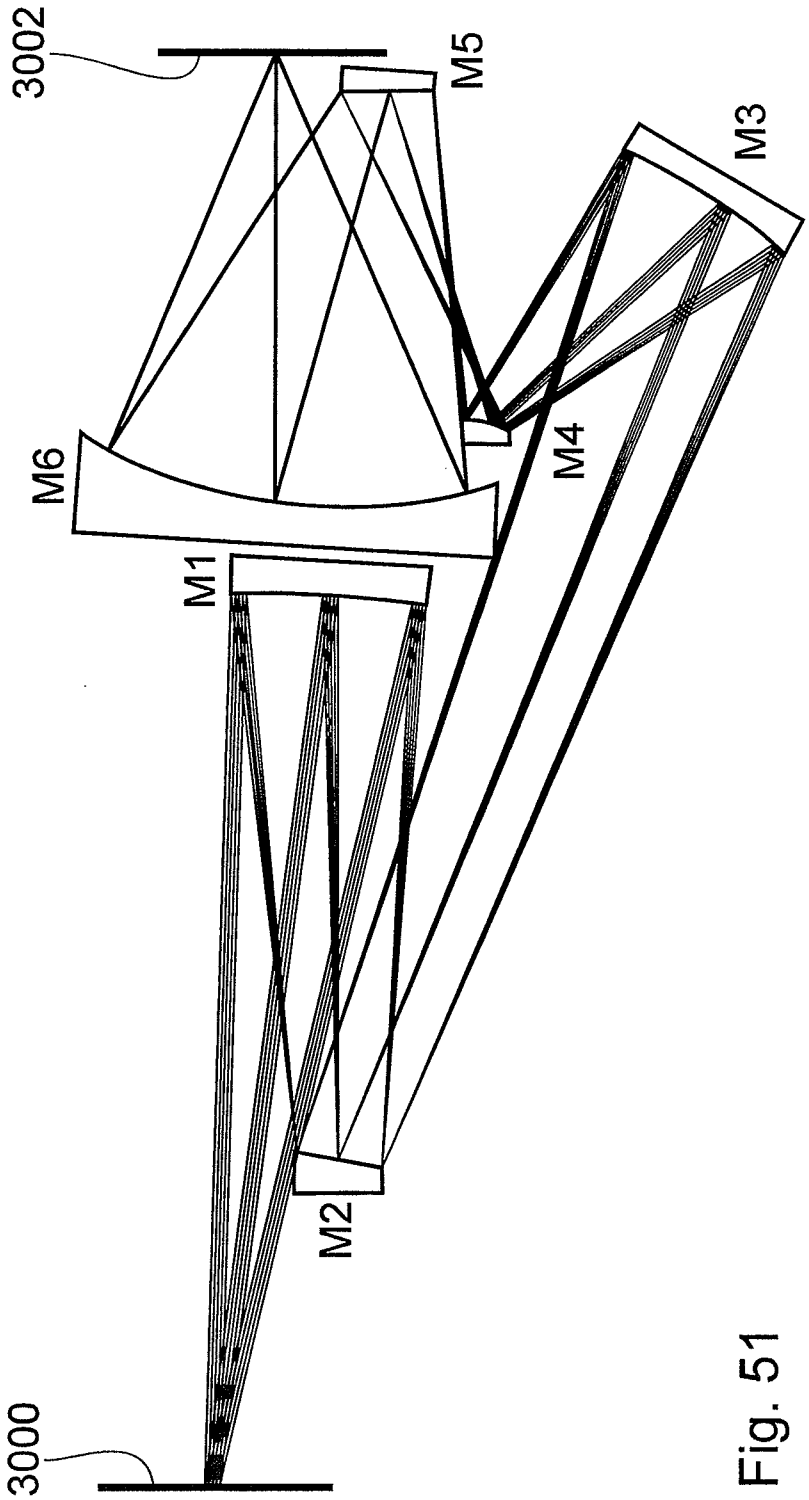


Fig. 51

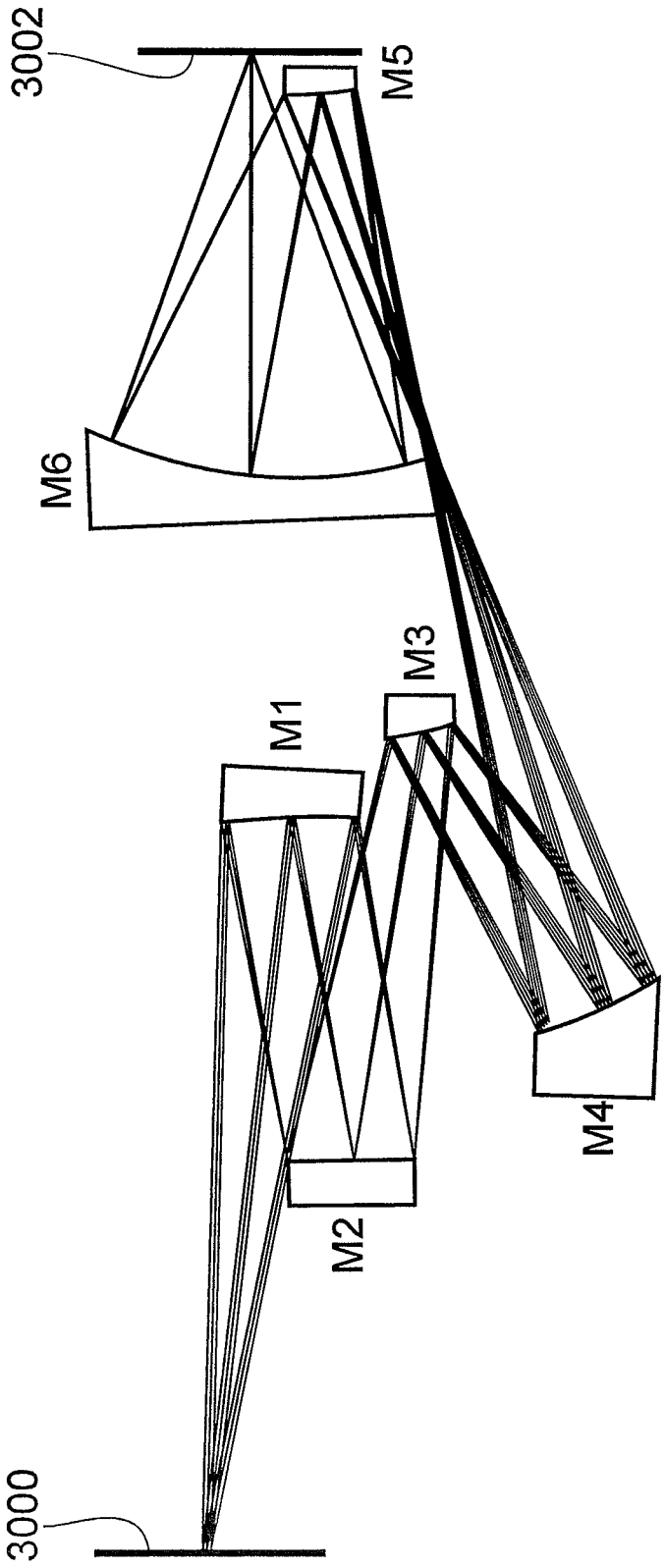


Fig. 52

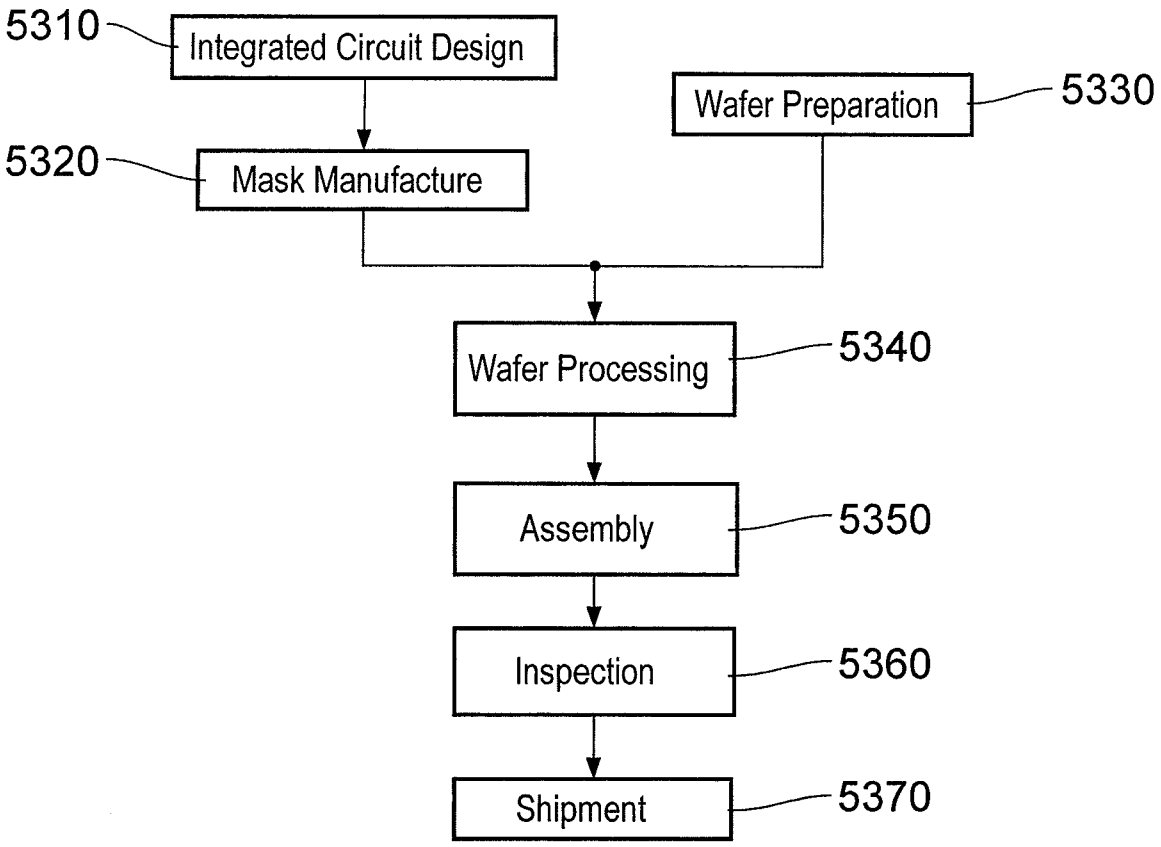

5310
Integrated Circuit Design
5320
Mask Manufacture
Wafer Preparation
5330
Wafer Processing
5340
Assembly
5350
Inspection
5360
Shipment
5370

Fig. 53

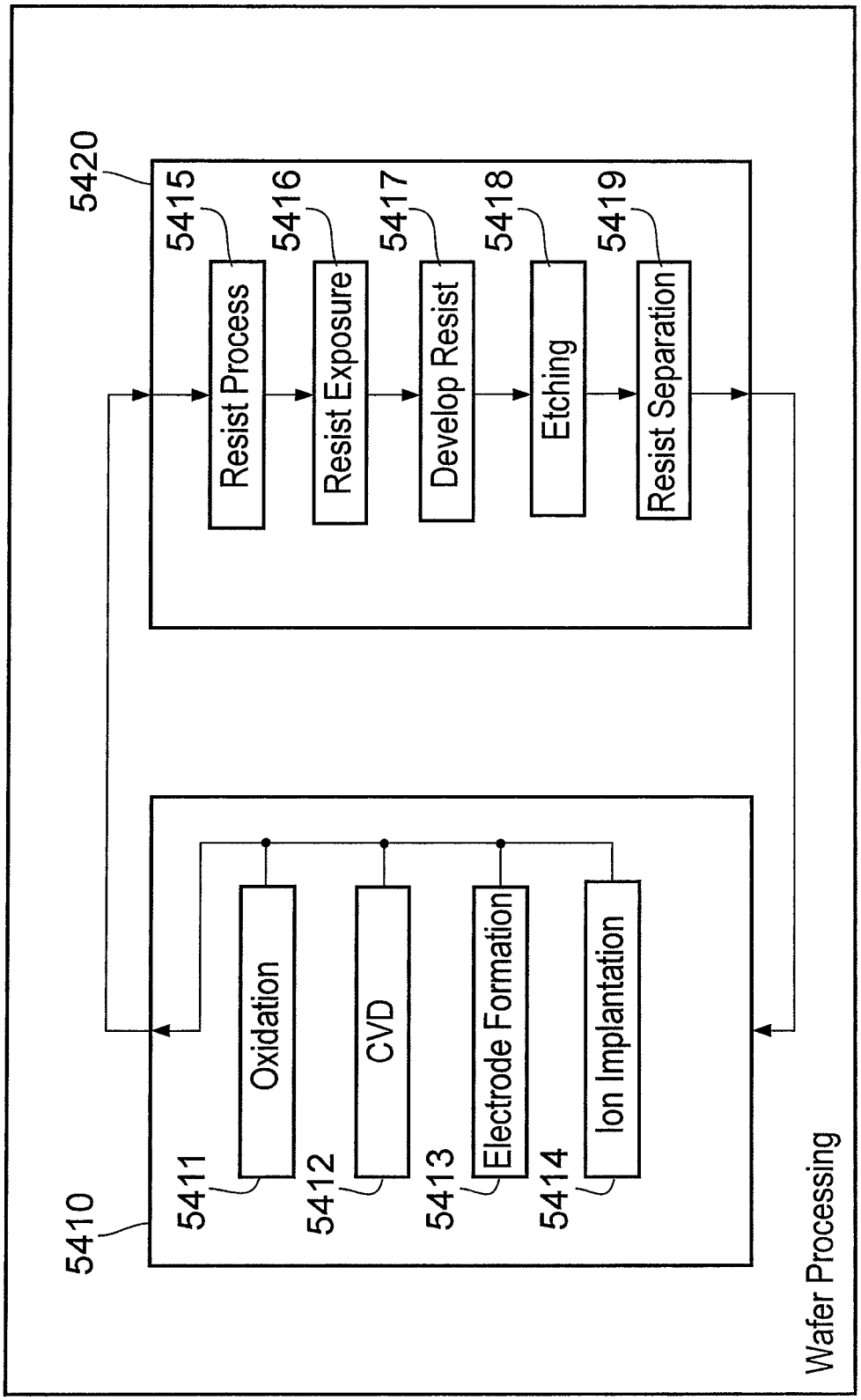

Wafer Processing
5410
5411
Oxidation
5412
CVD
5413
Electrode Formation
5414
Ion Implantation
5420
5415
Resist Process
5416
Resist Exposure
5417
Develop Resist
5418
Etching
5419
Resist Separation

Fig. 54